

MEMS Capacitor Sensors and Signal Conditioning

Dr. Lynn Fuller

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Electrical and Microelectronic Engineering

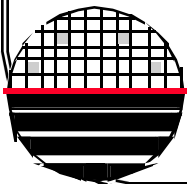
Rochester Institute of Technology

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Rochester, NY 14623-5604

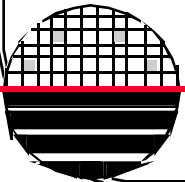
Email: Lynn.Fuller@rit.edu

Program Webpage: <http://www.microe.rit.edu>



OUTLINE

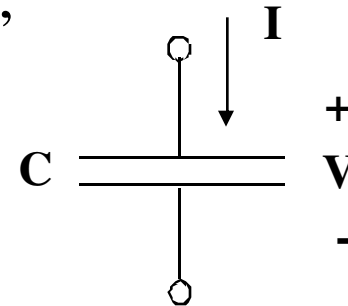
Capacitors
Capacitors as Sensors
Chemicapacitor
Diaphragm Pressure Sensor
Condenser Microphone
Capacitors as Electrostatic Actuators
Signal Conditioning
References
Homework



CAPACITORS

Capacitor - a two terminal device whose current is proportional to the time rate of change of the applied voltage;

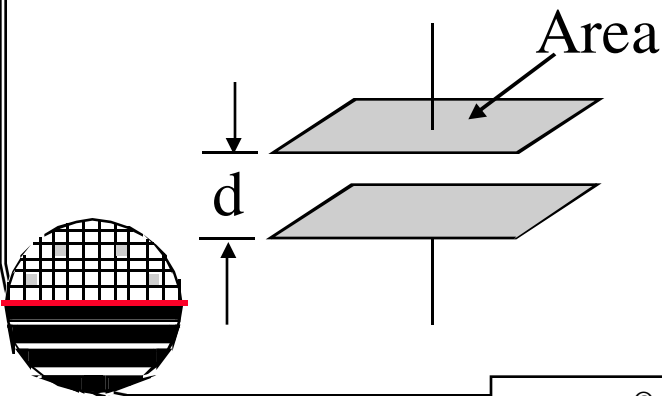
$$I = C \, dV/dt$$



a capacitor C is constructed of any two conductors separated by an insulator. The capacitance of such a structure is:

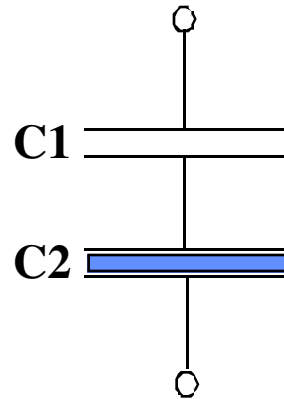
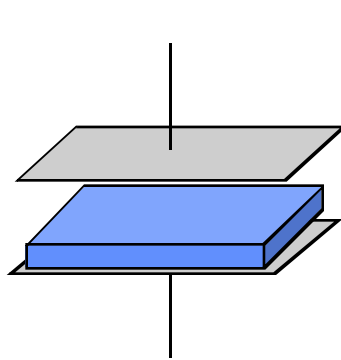
$$C = \epsilon_0 \epsilon_r \text{Area}/d$$

where ϵ_0 is the permittivity of free space
 ϵ_r is the relative permittivity
Area is the overlap area of the two
conductor separated by distance d
 $\epsilon_0 = 8.85E-14 \text{ F/cm}$
 $\epsilon_r \text{ air} = 1$
 $\epsilon_r \text{ SiO}_2 = 3.9$



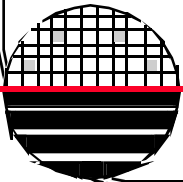
OTHER CAPACITOR CONFIGURATIONS

Two Dielectric Materials between Parallel Plates



$$C_{\text{Total}} = \frac{C1C2}{(C1+C2)}$$

Example: A condenser microphone is made from a polysilicon plate 100 μm square with 1000 \AA silicon nitride on it and a second plate of aluminum with a 1 μm air gap. Calculate C and C' if the aluminum plate moves 0.1 μm .

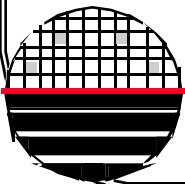


MEMS Capacitor Sensors

DIELECTRIC CONSTANT OF SELECTED MATERIALS

Vacuum	1
Air	1.00059
Acetone	20
Barium strontium titanate	500
Benzene	2.284
Conjugated Polymers	6 to 100,000
Ethanol	24.3
Glycerin	42.5
Glass	5-10

Methanol	30
Photoresist	3
Plexiglass	3.4
Polyimide	2.8
Rubber	3
Silicon	11.7
Silicon dioxide	3.9
Silicon Nitride	7.5
Teflon	2.1
Water	80-88



<http://www.asiinstruments.com/technical/Dielectric%20Constants.htm>

MEMS Capacitor Sensors

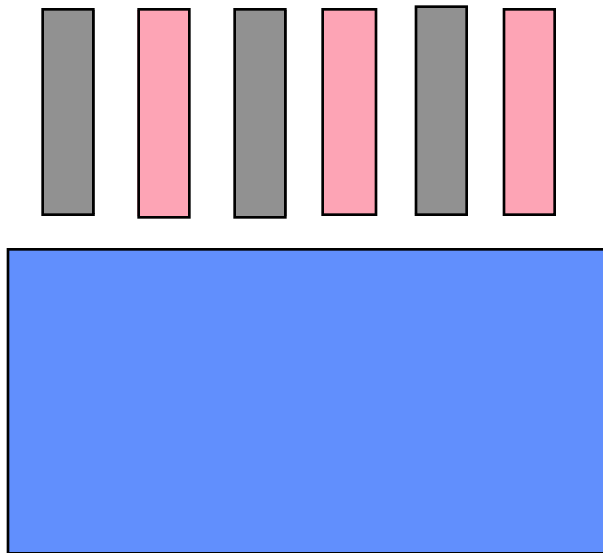
CALCULATIONS

	A	B	C	D	E	F	G	H	I
1	Rochester Institute of Technology								8-Apr-08
2	Dr. Lynn Fuller		Microelectronic Engineering, 82 Lomb Memorial Dr., Rochester, NY 14623						
3									
4	To use this spread sheet enter values in the white boxes. The rest of the sheet is protected and should not be								
5	changed unless you are sure of the consequences. The results are displayed in the purple boxes.								
6									
7	Capacitance of Two Parallel Plates								
8	Capacitance = $\epsilon_0 \epsilon_r \text{Area}/d$					C =	8.85E-12	F	
9						ϵ_0 = Permittivity of free space	8.85E-14	F/cm	
10						ϵ_r = relative permittivity =	1		
11						Area =	1.00E-02	cm ²	
12						number of pairs of plates, N =	1		
13						distance between plates, d =	1	μm	
14						If round plates, Diameter =	0	μm	
15						If rectangular plates, length =	1000	μm	
16						If rectangular plates, width =	1000	μm	
17	Force Between Two Parallel Plates					Force =	4.43E-04	N	
18	Electrostatic Force = $\epsilon_0 \epsilon_r \text{Area } V^2/2d^2$				Applied Voltage, V =	10	volts		
19									
20	Capacitance for very Thick Interdigitated Fingers								
21	C = (N-1) $\epsilon_0 \epsilon_r L h/s$				Capacitance, C =	1.77E-13	F		
22						Number of Fingers, N =	101		

Microelectronic Engineering

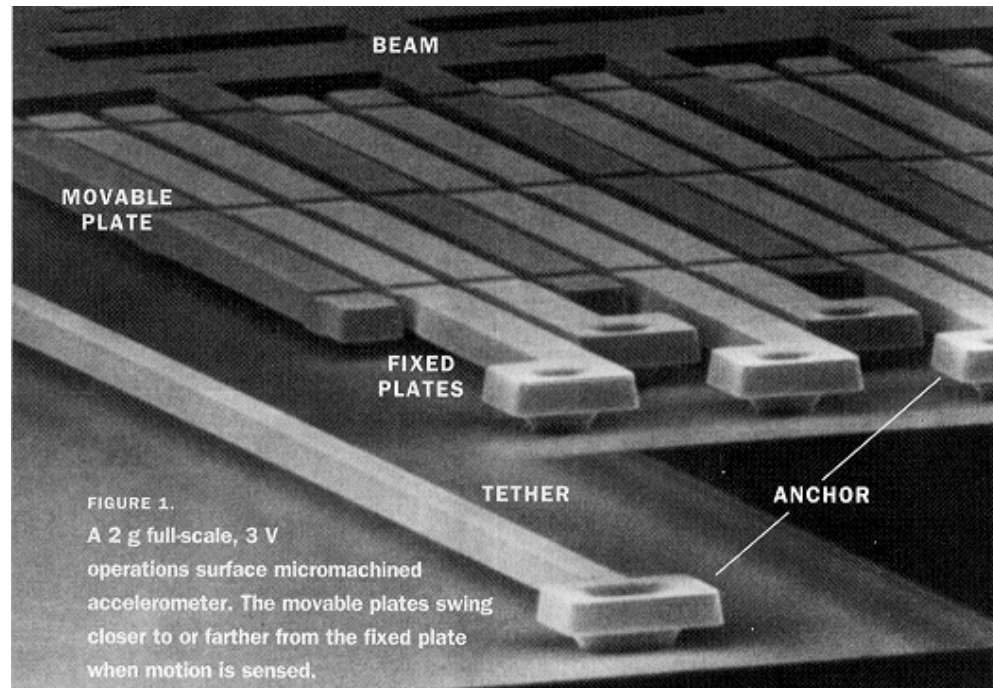
OTHER CAPACITOR CONFIGURATIONS

Interdigitated Fingers with Thickness $>$ Space between Fingers

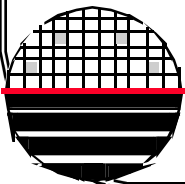


$$C = (N-1) \epsilon_0 \epsilon_r L h / s$$

- h = height of fingers
- s = space between fingers
- N = number of fingers
- L = length of finger overlap

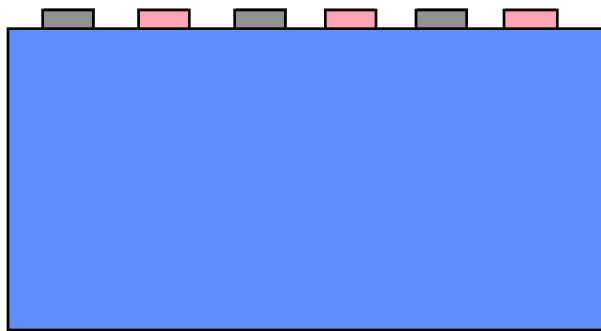


Example:



OTHER CAPACITOR CONFIGURATIONS

Interdigitated Fingers with Thickness \ll Space between Fingers



$$C = LN \left[\frac{4 \epsilon_0 \epsilon_r}{\pi} \right] \sum_{n=1}^{\infty} \frac{1}{2n-1} J_0^2 \left[\frac{(2n-1)\pi s}{2(s+w)} \right]$$

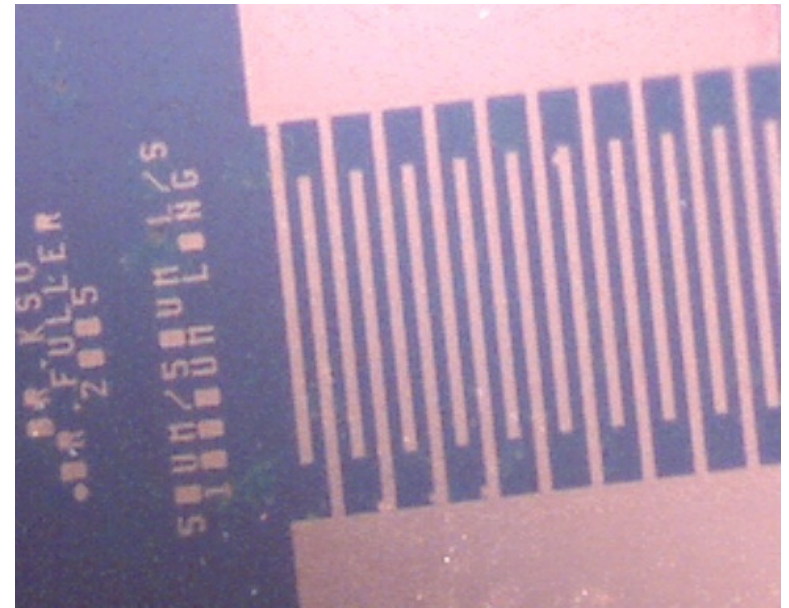
J_0 = zero order Bessel function

w = width of fingers

s = space between fingers

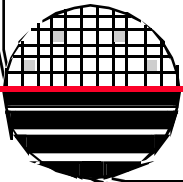
N = number of fingers

L = length of finger overlap



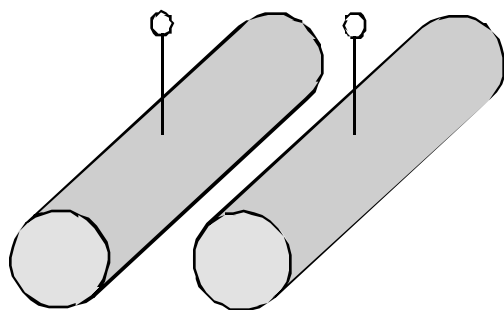
Reference:

Lvovich, Liu and Smiechowski,



OTHER CAPACITOR CONFIGURATIONS

Two Long Parallel Wires Surrounded by Dielectric Material



Capacitance per unit length C/L

$$C/L = 12.1 \epsilon_r / (\log [(h/r) + ((h/r)^2 - 1)^{1/2}])$$

h = half center to center space

r = conductor radius (same units as h)

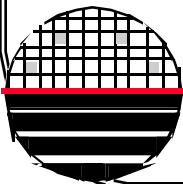
Reference: Kraus and Carver

Example: Calculate the capacitance of a meter long connection of parallel wires.

Solution: let, h = 1 mm, r = 0.5mm, plastic $\epsilon_r = 3$ the equation above gives

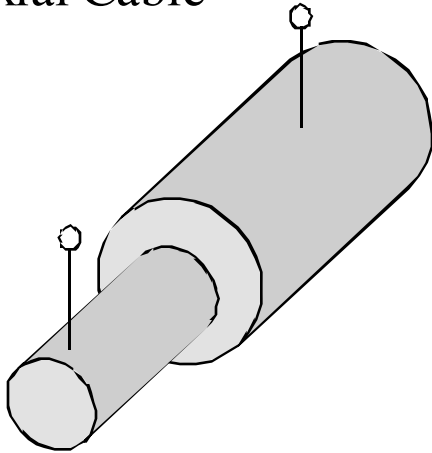
$$C/L = 63.5 \text{ pF/m}$$

$$C = 63.5 \text{ pF}$$



OTHER CAPACITOR CONFIGURATIONS

Coaxial Cable



Capacitance per unit length C/L

$$C/L = 2 \pi \epsilon_0 \epsilon_r / \ln(b/a)$$

b = inside radius of outside conductor

a = radius of inside conductor

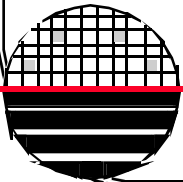
Reference: Kraus and Carver

Example: Calculate the capacitance of a meter long coaxial cable.

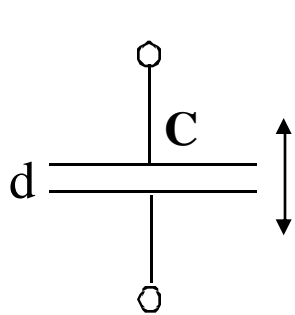
Solution: let $b = 5$ mm, $a = 0.2$ mm, plastic $\epsilon_r = 3$ the equation above gives

$$C/L = 51.8 \text{ pF/m}$$

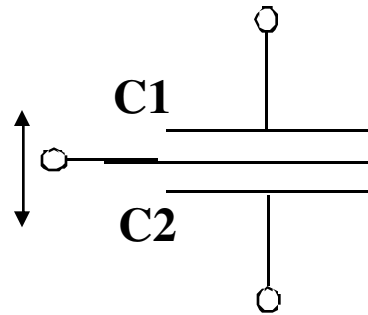
$$C = 51.8 \text{ pF}$$



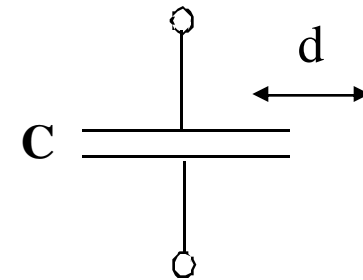
CAPACITORS AS SENSORS



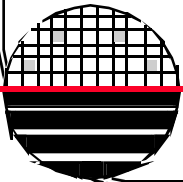
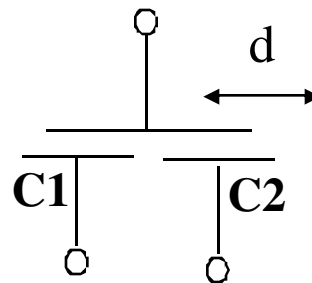
One plate moves relative to other changing gap (d)



Center plate moves relative to the two fixed plates



One plate moves relative to other changing overlap area (A)



CAPACITORS AS SENSORS

Change in Space Between Plates (d)

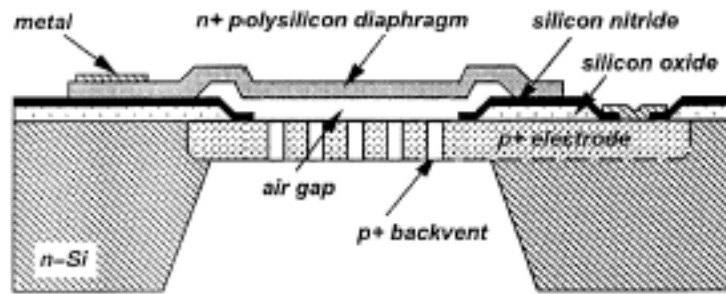
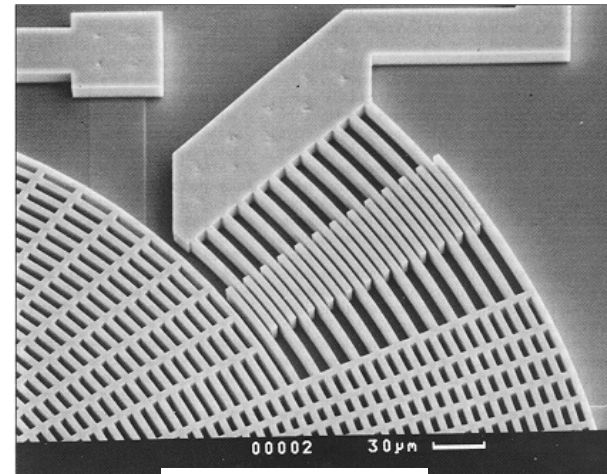


Figure 1: Cross section of the polysilicon diaphragm condenser microphone

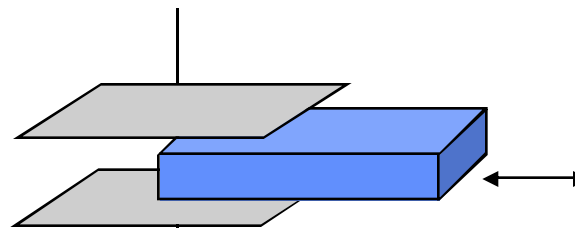
microphone

Change in Area (A)

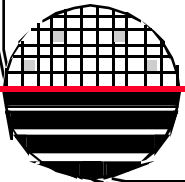


gyroscope

Change in Dielectric Constant (ϵ_r)



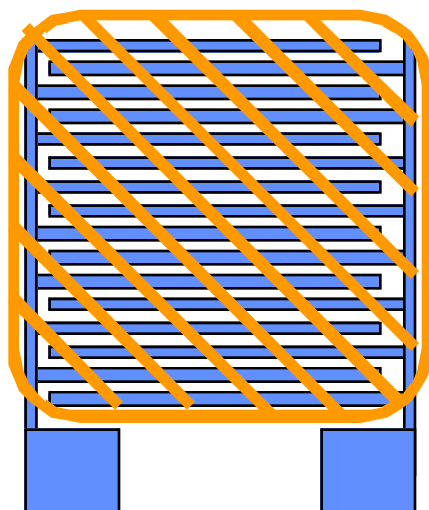
position sensor



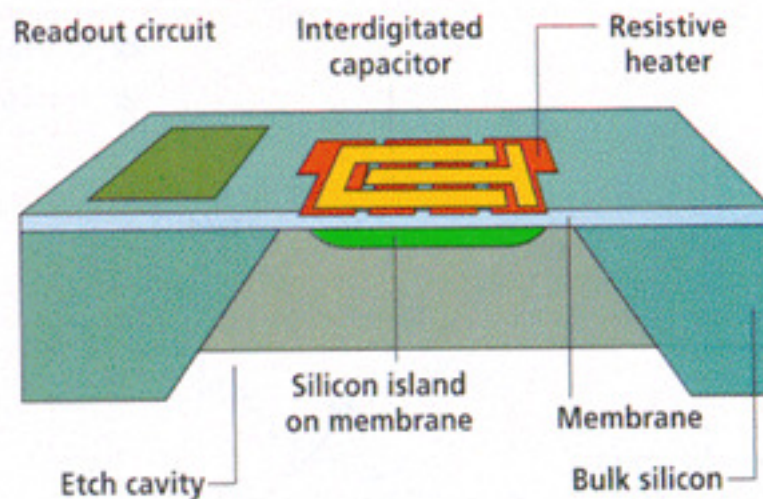
MEMS Capacitor Sensors

CHEMICAL SENSOR

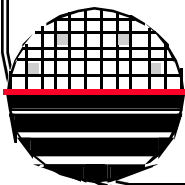
Two conductors separated by a material that changes its dielectric constant as it selectively absorbs one or more chemicals. Some humidity sensors are made using a polymer layer as a dielectric material.



Change in Dielectric Constant (ϵ_r)

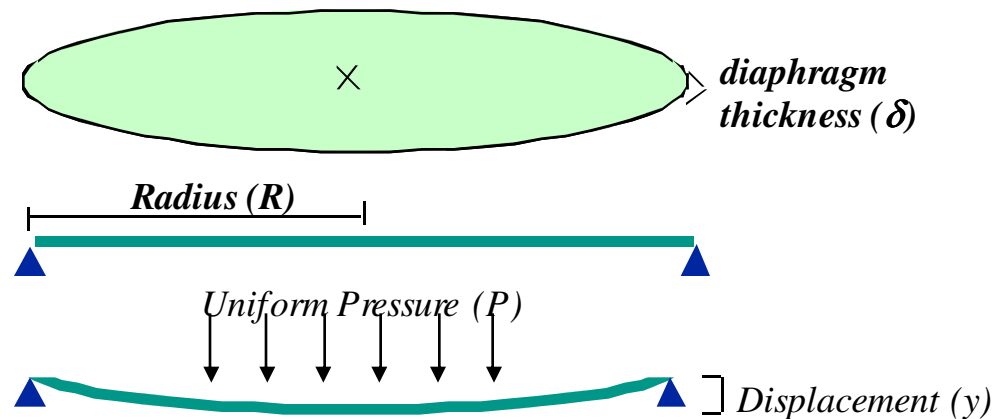


chemical sensor



DIAPHRAGM PRESSURE SENSOR

**Diaphragm:
Displacement**



Equation for deflection at center of diaphragm

$$y = \frac{3PR^4[(1/\nu)^2-1]}{16E(1/\nu)^2\delta^3} = \frac{(249.979)PR^4[(1/\nu)^2-1]}{E(1/\nu)^2\delta^3}$$

E = Young's Modulus, ν = Poisson's Ratio
for Aluminum $\nu = 0.35$

*The second equation corrects all units assuming that pressure is mmHg, radius and diaphragm is μm , Young's Modulus is dynes/cm², and the calculated displacement found is μm .

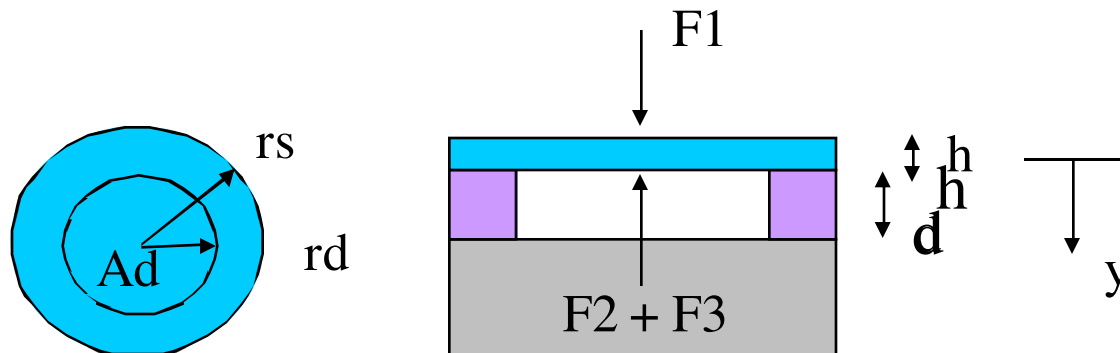
DIAPHRGM WITH CAPTURED VOLUME

$$PV = nRT$$

F1 = force on diaphragm = external pressure times area of diaphragm

F2 = force due to captured volume of air under the diaphragm

F3 = force to mechanically deform the diaphragm

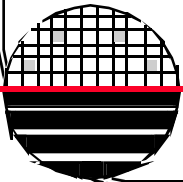


$$F1 = F2 + F3 \quad F1 = P \times Ad \quad F2 = nRT Ad / (Vd + Vs)$$

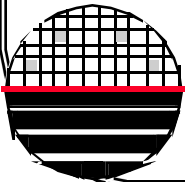
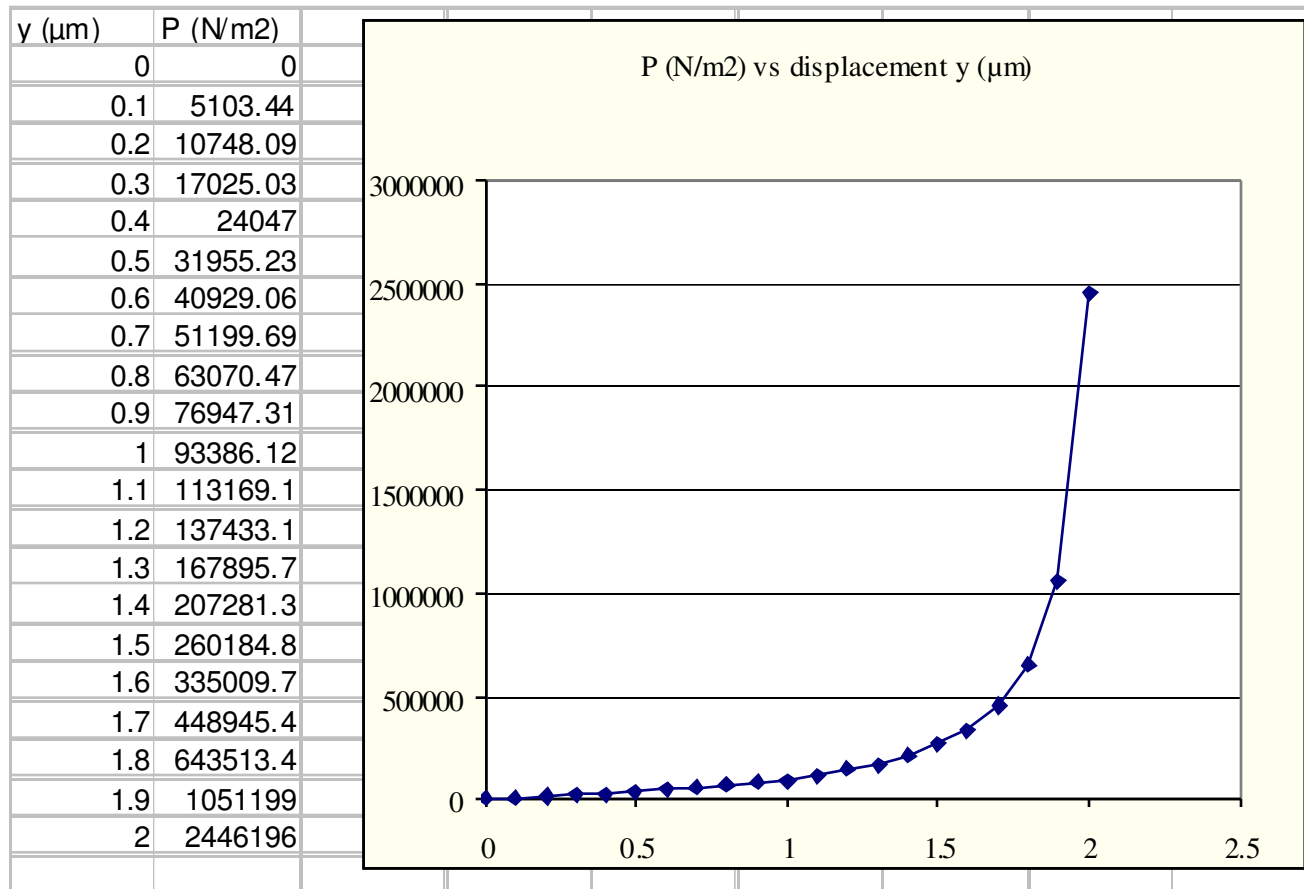
where $Vd = Ad (d-y)$ and $Vs = G1 Pi (rs^2 - rd^2)(d)$ where

G1 is the % of spacer that is not oxide

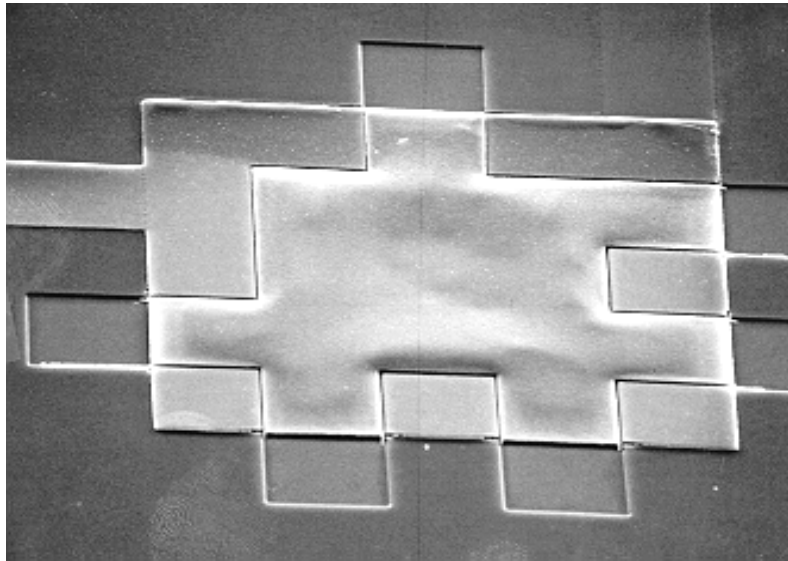
$$F3 = (16 E (1/\nu)^2 h^3 y) / (3 rd^4 [(1/\nu)^2 - 1])$$



DIAPHRAGM WITH CAPTURED VOLUME



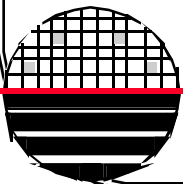
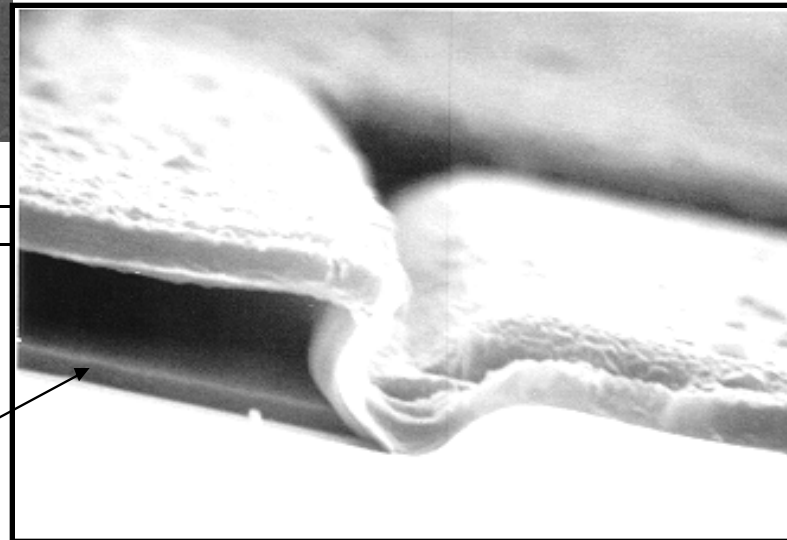
CONDENSER MICROPHONE



ALUMINUM DIAPHRAGM

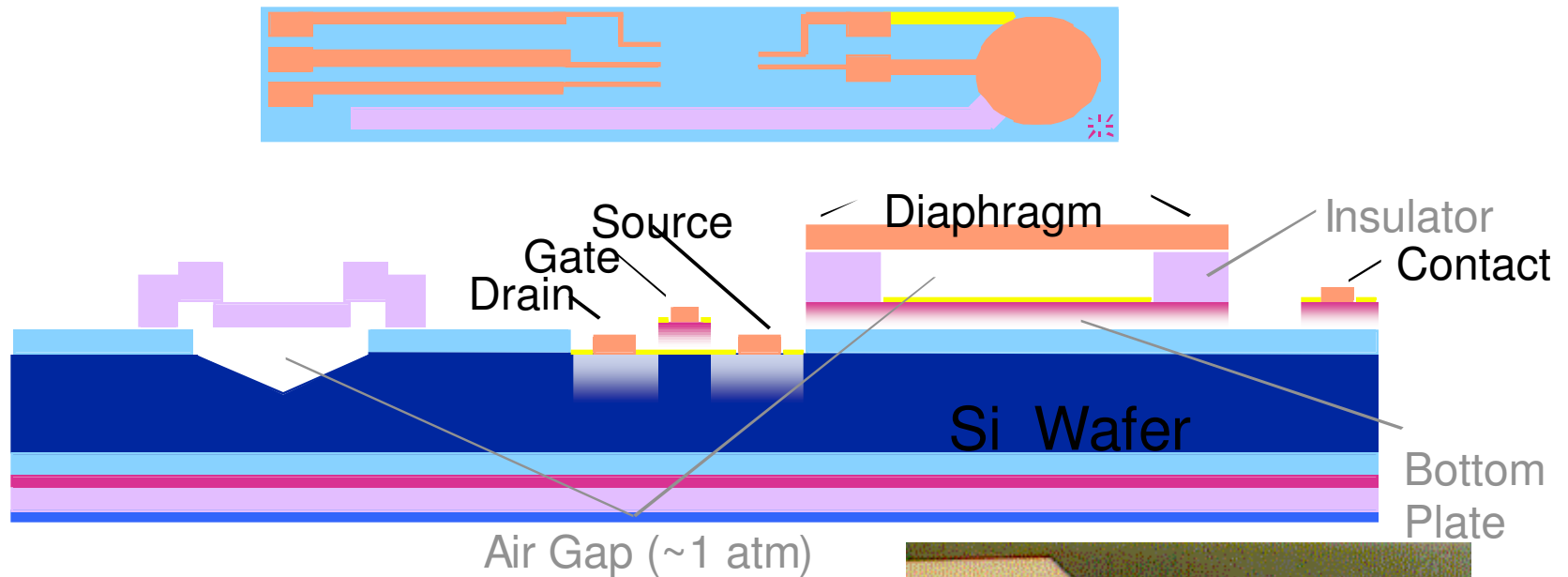
1 μm Aluminum

2.0 μm Gap

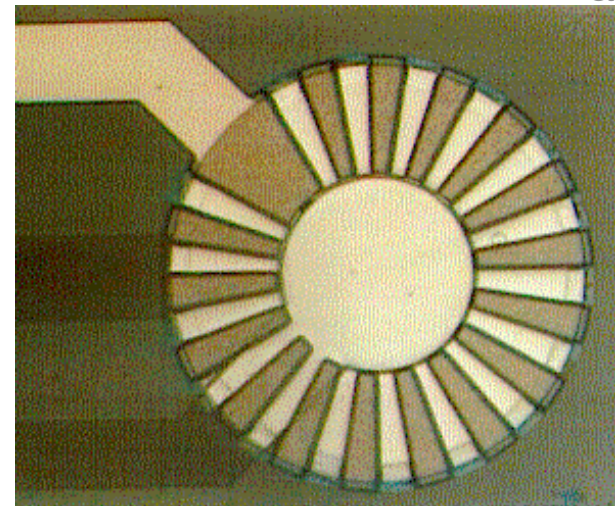


MEMS Capacitor Sensors

ALUMINUM DIAPHRAGM PRESSURE SENSOR



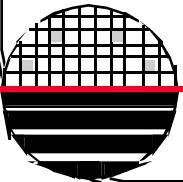
Kerstin Babbitt - University of Rochester
Stephanie Bennett - Clarkson University
Sheila Kahwati - Syracuse University
An Pham - Rochester Institute of Technology



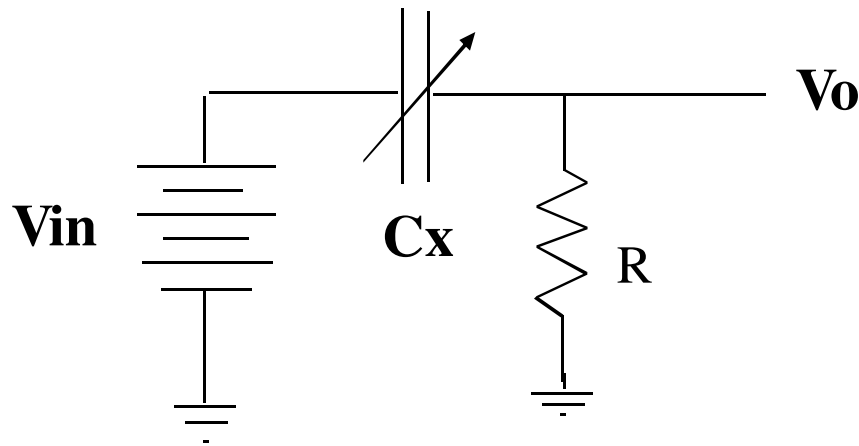
Rochester Institute of Technology
Microelectronic Engineering

SIGNAL CONDITIONING FOR CAPACITOR SENSORS

Delta Capacitance to AC Voltage
Static Capacitance to DC Voltage
Capacitance to Current
Ring Oscillator Capacitance to Frequency
RC Oscillator Capacitance to Frequency
Frequency to Digital
Capacitance to Analog Voltage to Digital
Other
Wireless

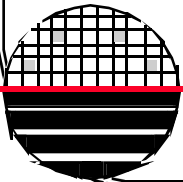


DELTA CAPACITANCE TO AC VOLTAGE



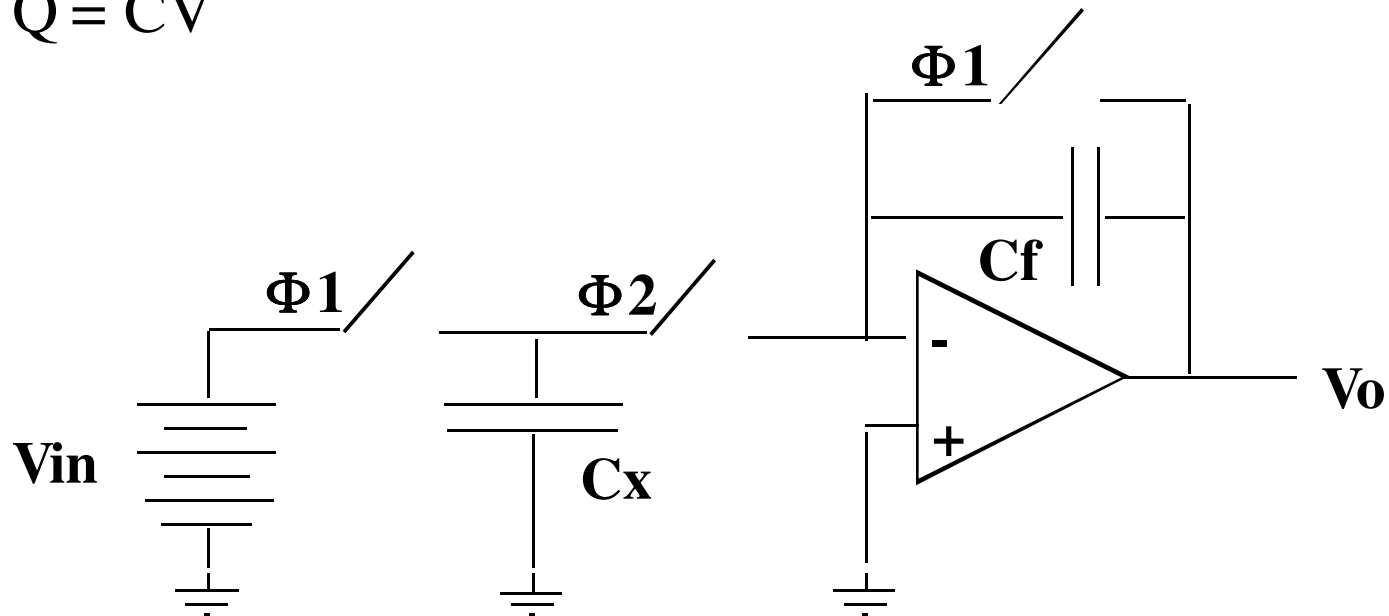
If C_x is fixed V_o is zero. If C_x changes there will be a change in current and a corresponding change in V_o

Example: Let $V_{in} = 3$ volts, $C = 10$ pF, microphone action causes C to change by 0.1 pF at 1000 Hz. Calculate the output voltage.

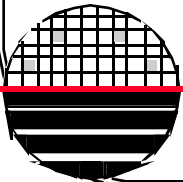


STATIC CAPACITANCE TO DC VOLTAGE

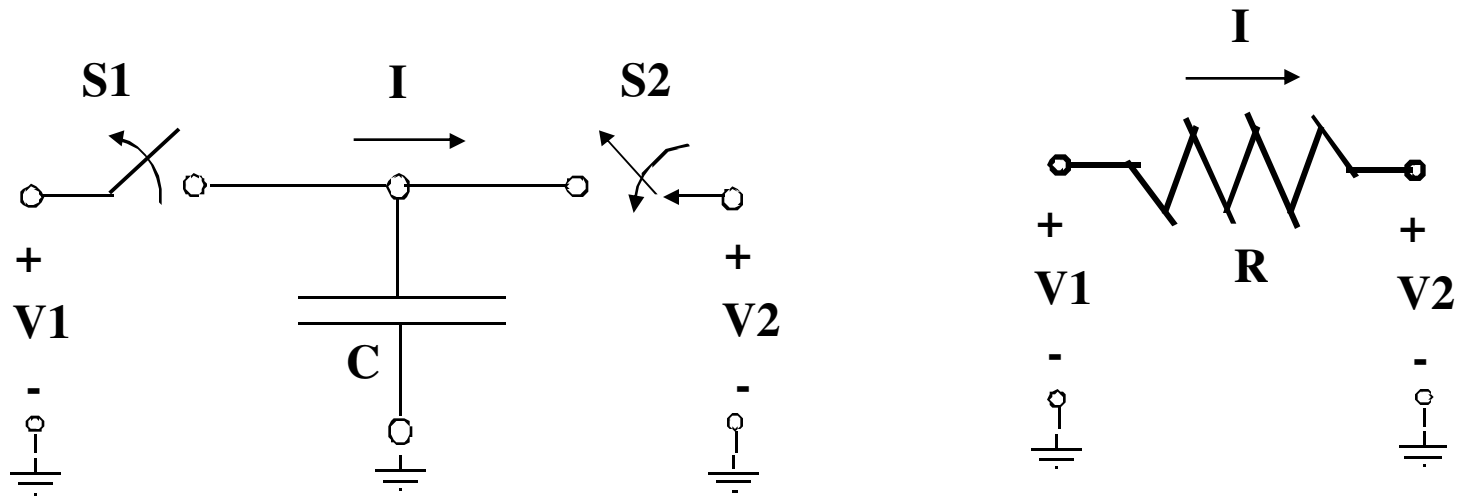
$$Q = CV$$



$$V_o = - V_{in} C_x / C_f$$



SWITCHED CAPACITOR EQUIVALENT RESISTOR



$$I = Cfs (V_1 - V_2)$$

$$I = (1/R) (V_1 - V_2)$$

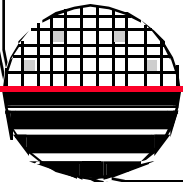
S1 closed C charges to V_1 , charge transferred is $Q = CV_1$

S1 is opened

S2 is closed C charges to V_2 , charge transferred is $Q = CV_2$

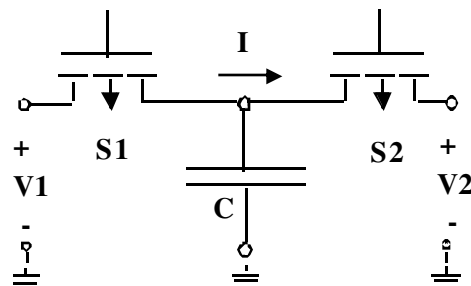
if the switches operate at a switching frequency f_s , then $I = Qf_s = Cfs(V_1 - V_2)$

and $R_{eq} = 1/(Cfs)$

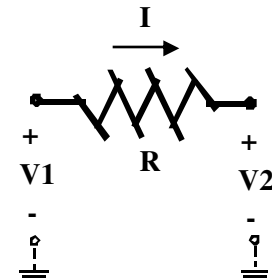


SC EXAMPLE

1. The sampling frequency f_s must be much higher than the signal frequencies
2. The voltages at node 1 and 2 must be unaffected by switch closures.
3. The switches are ideal.
4. S1 and S2 are not both on at same time. (use non overlapping clocks)



$$R_{eq} = 1/(Cf_s)$$

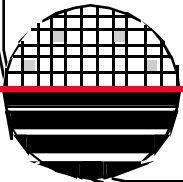


$$I = (1/R) (V1 - V2)$$

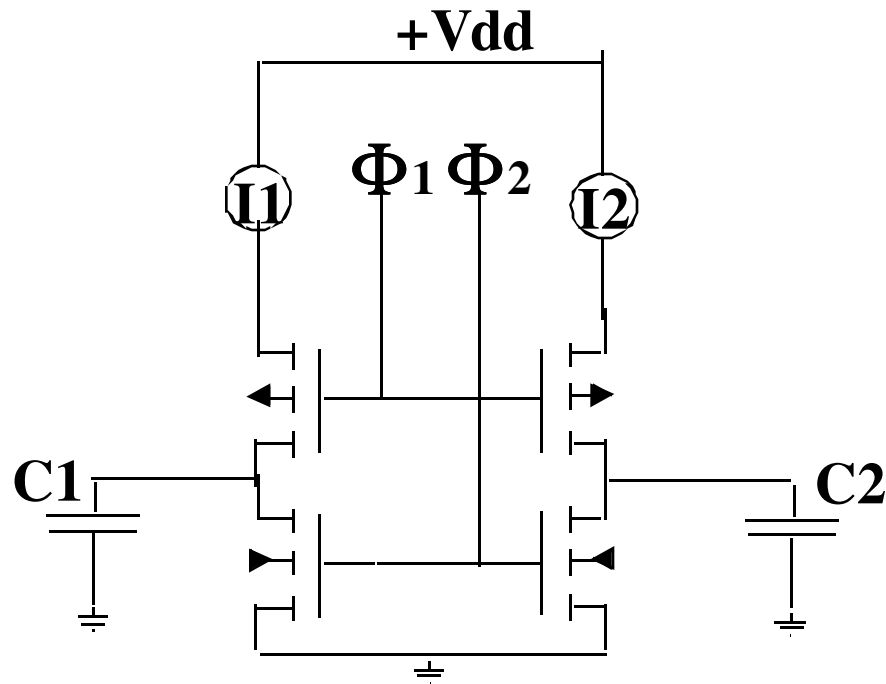
Example: for audio applications with frequencies up to 10KHz, we select switch frequency of 500KHz, for a 1 MEG ohm resistor we find that

$$C = 1/ (500K \cdot 1MEG) = 2 \text{ p/F}$$

If $X_{ox} = 500 \text{ \AA}$, then the capacitor will be about $30 \mu\text{m}$ by $30 \mu\text{m}$

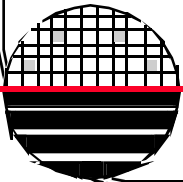
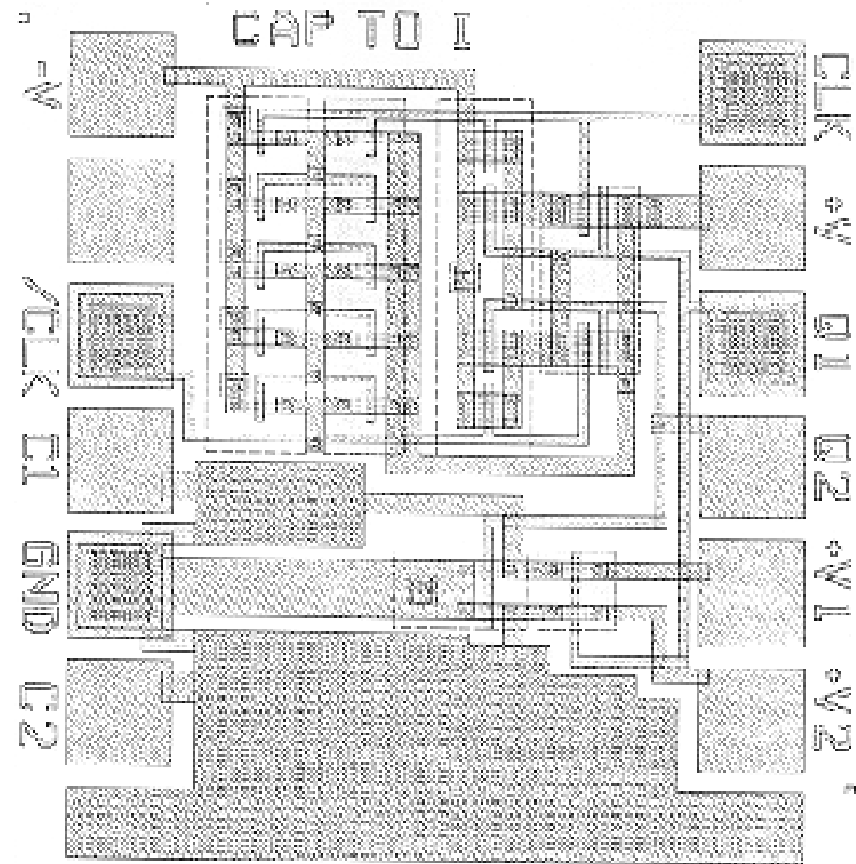


CAPACITANCE TO CURRENT

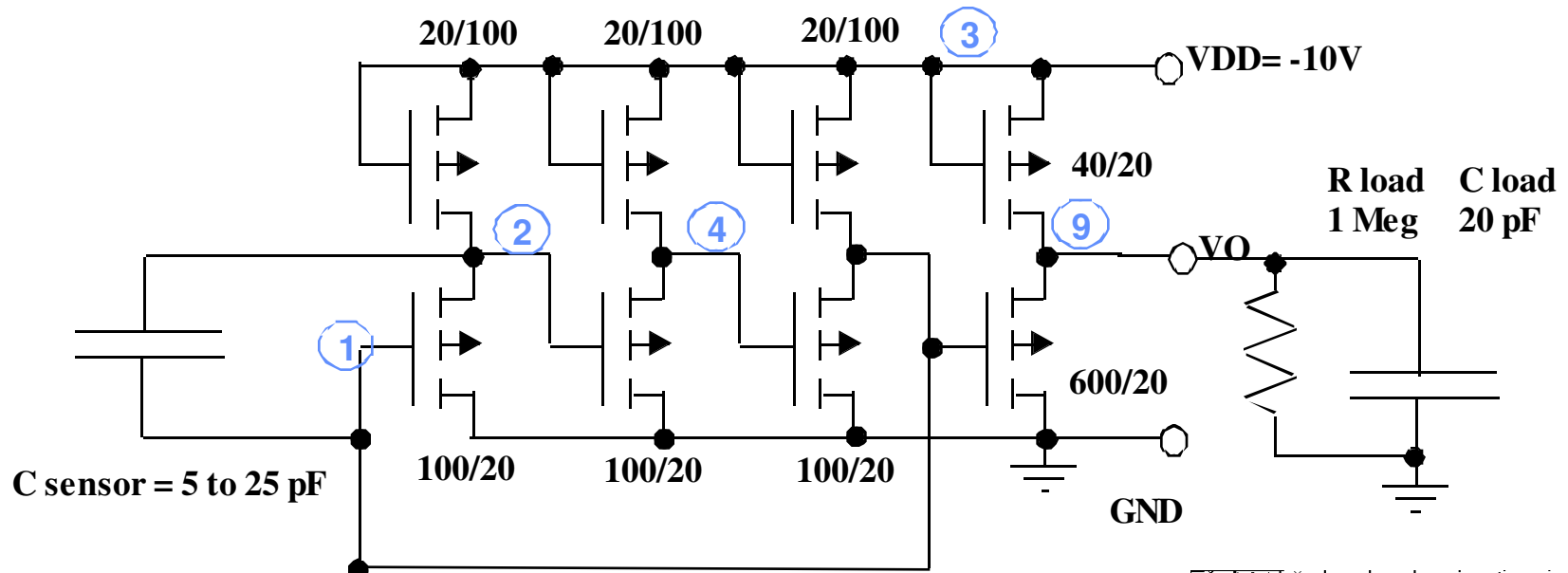


$$I_2 - I_1 = V_{dd} f (C_2 - C_1)$$

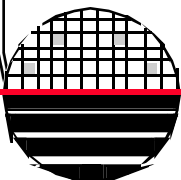
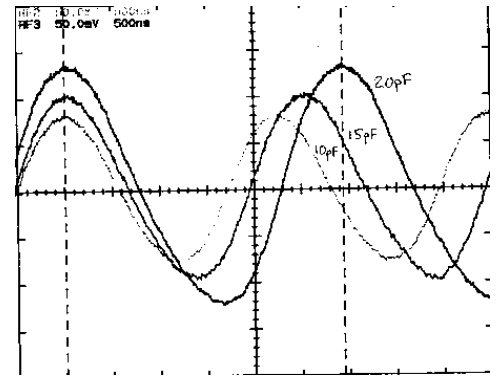
where f is the clock frequency



RING OSCILLATOR, C TO FREQUENCY



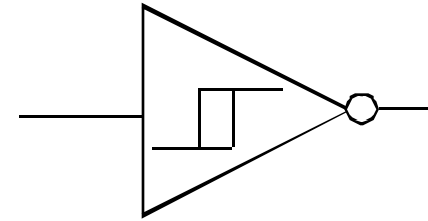
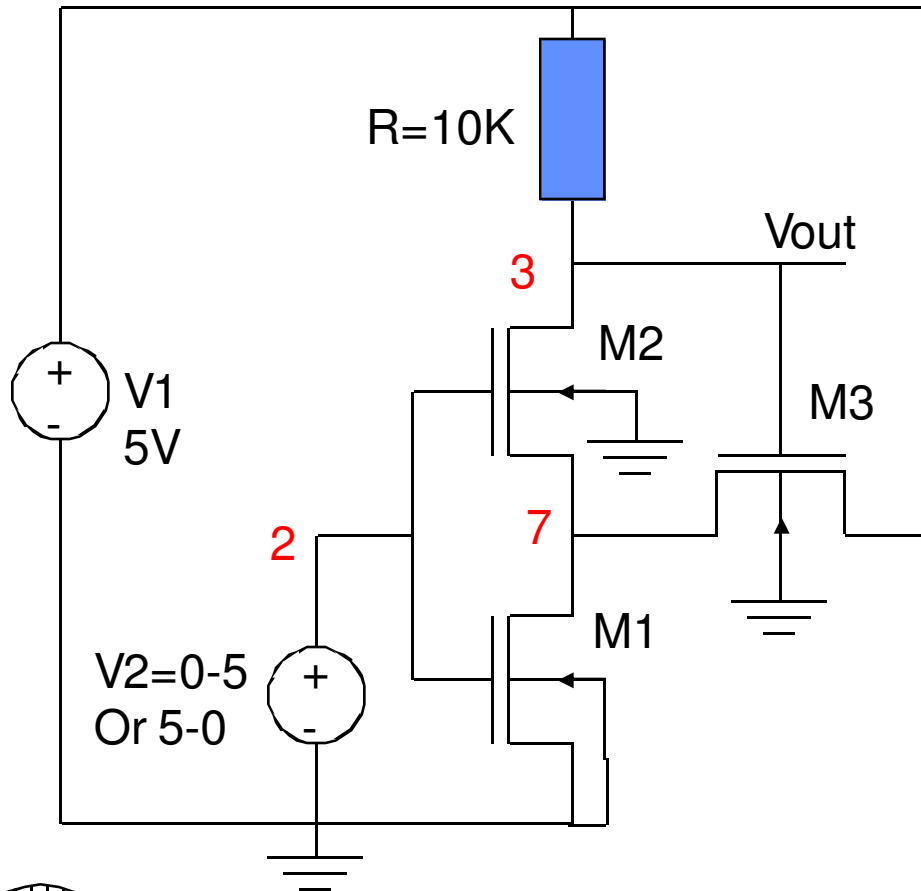
$C \text{ sensor} = 5 \text{ to } 25 \text{ pF}$
 $C \text{ parasitic} = 10\text{pF}$
 $t_d = T/2N$
 $T = \text{period of oscillation}$
 $N = \text{number of stages}$



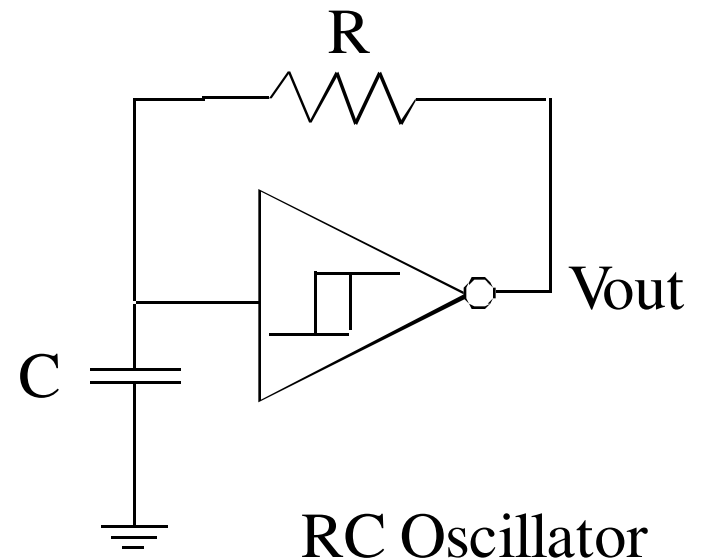
MEMS Capacitor Sensors

RC OSCILLATOR USING INVERTER WITH HYSTERESIS

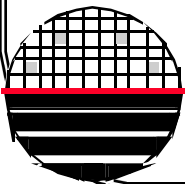
1



Inverter with Hysteresis



RC Oscillator



Microelectronic Engineering

INVERTER WITH HYSTERESIS

INVERTER WITH HYSTERESIS USING FOR RIT SUB-CMOS NMOSFET, Dr. Lynn Fuller, v

*LINE ABOVE IS TITLE

*START WIN SPICE AND ENTER LOCATION AND NAME OF INPUT FILE

*THIS FILE IS HYSTERESIS.TXT

*EXAMPLE: winspice> source c:/spice/Hysteresis.txt

*THE TRANSISTOR MODELS ARE IN THE FILE NAMED BELOW

.INCLUDE E:\SPICE\WINSPICE\RIT_MICROE_MODELS.TXT

*CIRCUIT DESCRIPTION

*VOLTAGE SOURCES

V1 1 0 DC 5

V2 2 0 DC 0

*TRANSISTORS

M1 7 2 0 0 RITSUBN49 L=2U W=16U ad=96e-12 as=96e-12 pd=44e-6 ps=44e-6 nrd=0.025 nrs=0.025

M2 3 2 7 0 RITSUBN49 L=2U W=16U ad=96e-12 as=96e-12 pd=44e-6 ps=44e-6 nrd=0.025 nrs=0.025

M3 1 3 7 0 RITSUBN49 L=2U W=16U ad=96e-12 as=96e-12 pd=44e-6 ps=44e-6 nrd=0.025 nrs=0.025

*RESISTORS

R1 1 3 10000

*REQUESTED ANALYSIS

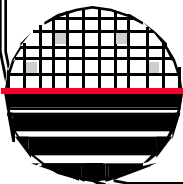
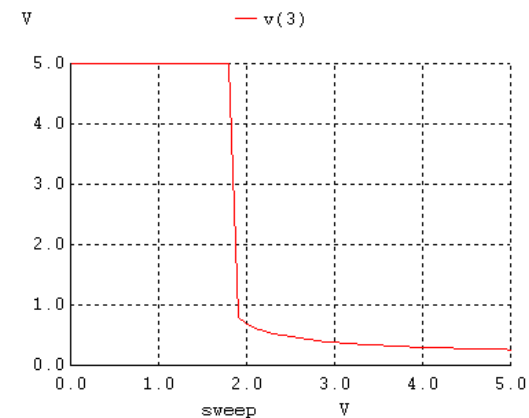
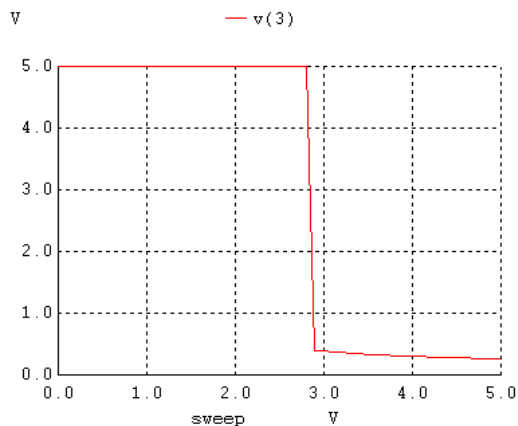
.OP

.DC V2 5 0 -.1

*.DC V2 0 5 .1

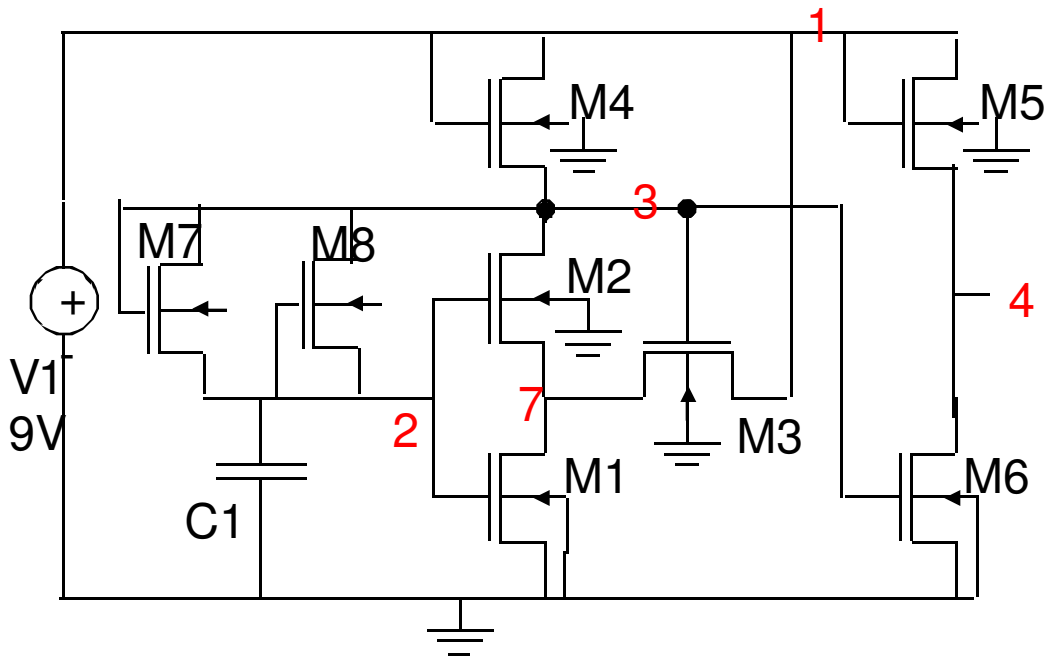
.PLOT DC V(3)

.END

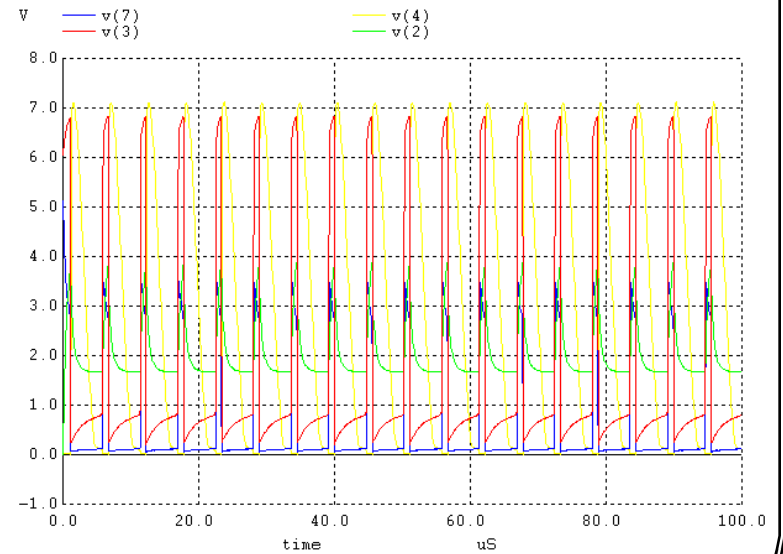
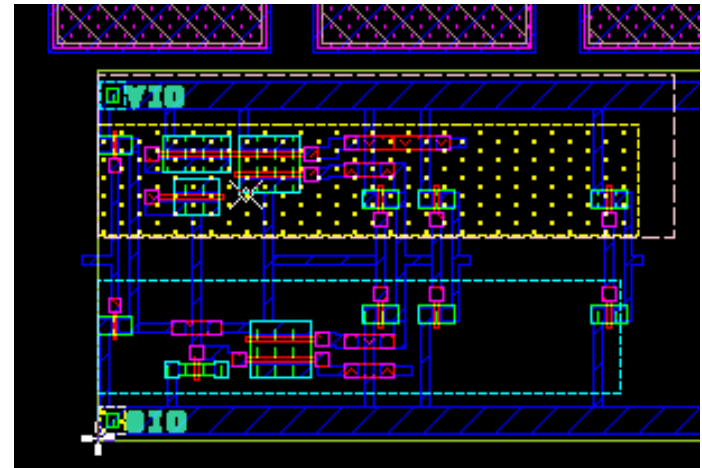


MEMS Capacitor Sensors

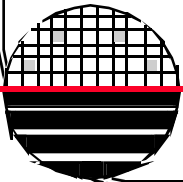
RC OSCILLATOR, INVERTER WITH HYSTERESIS



All PMOS Realization



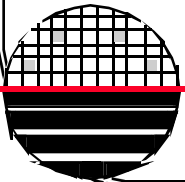
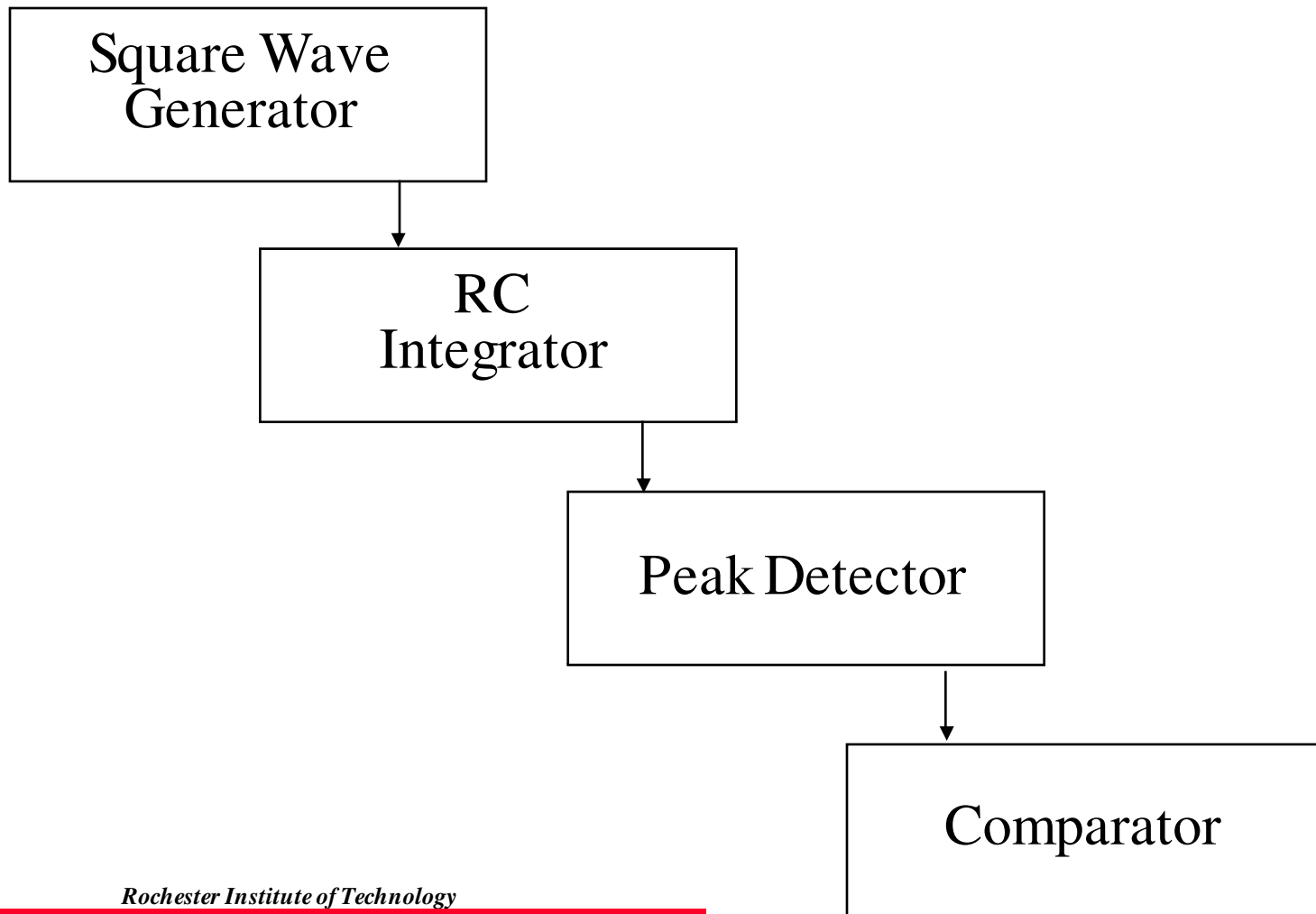
3.0pF



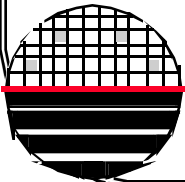
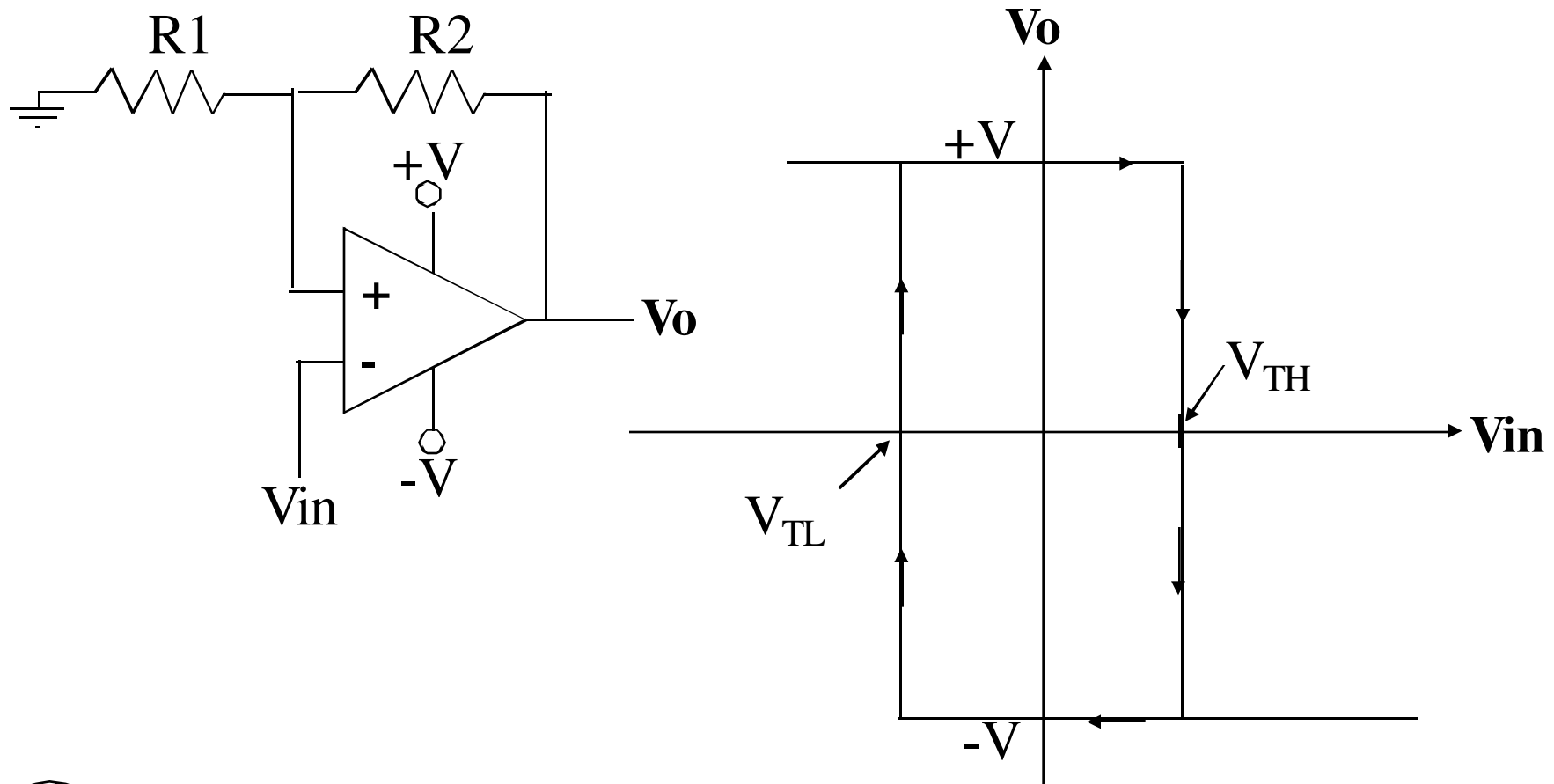
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DESIGN EXAMPLE

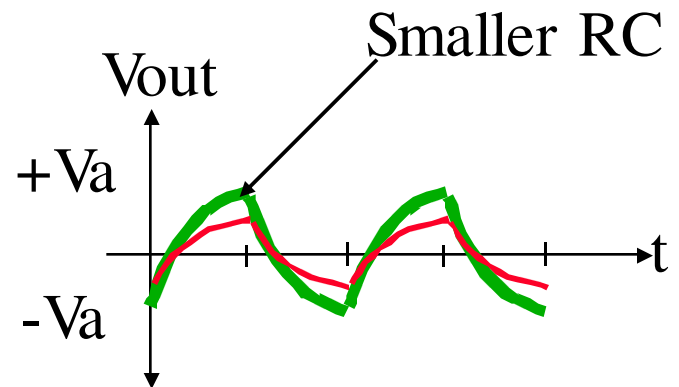
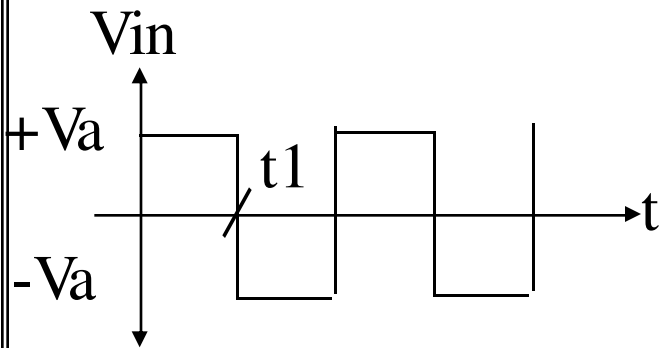
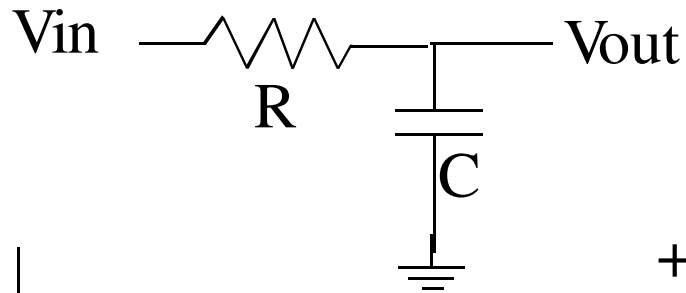


BISTABLE MULTIVIBRATOR



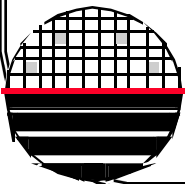
MEMS Capacitor Sensors

RC INTEGRATOR

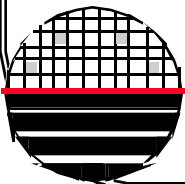
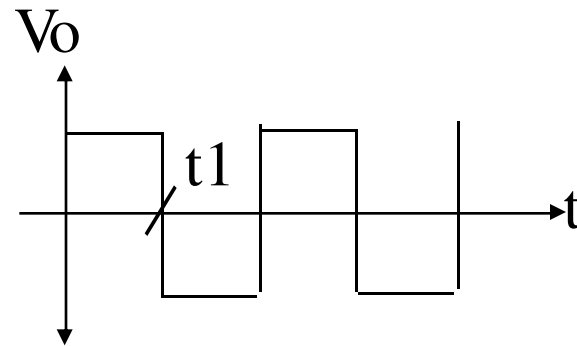
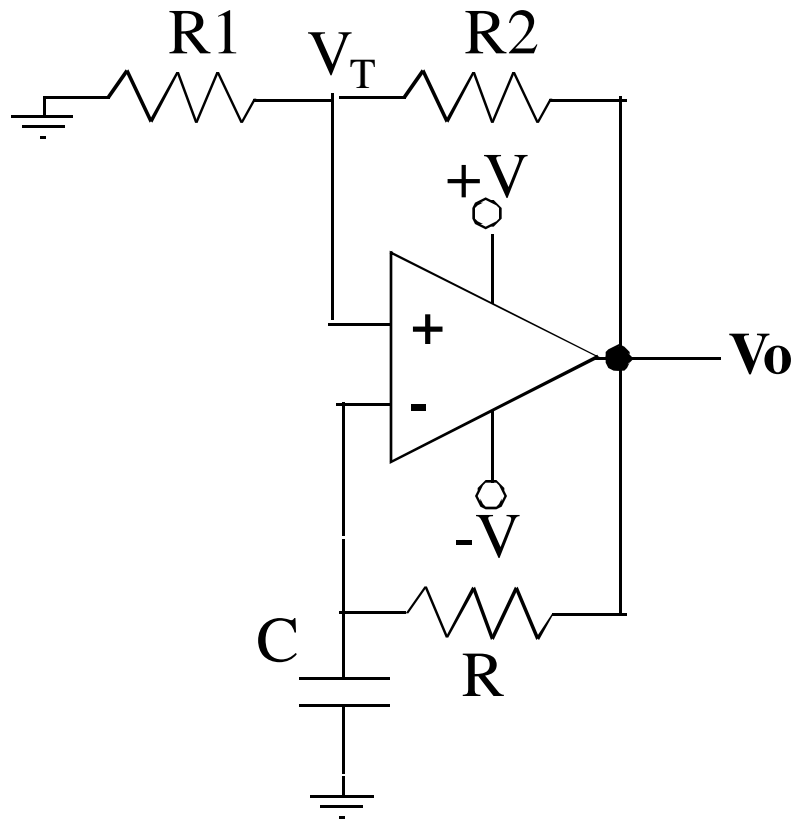


$$V_{out} = (-V_a) + [2V_a(1 - e^{-t/RC})] \quad \text{for } 0 < t < t_1$$

If $R=1\text{MEG}$ and $C=10\text{pF}$ find $RC=10\mu\text{s}$

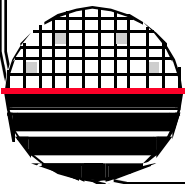
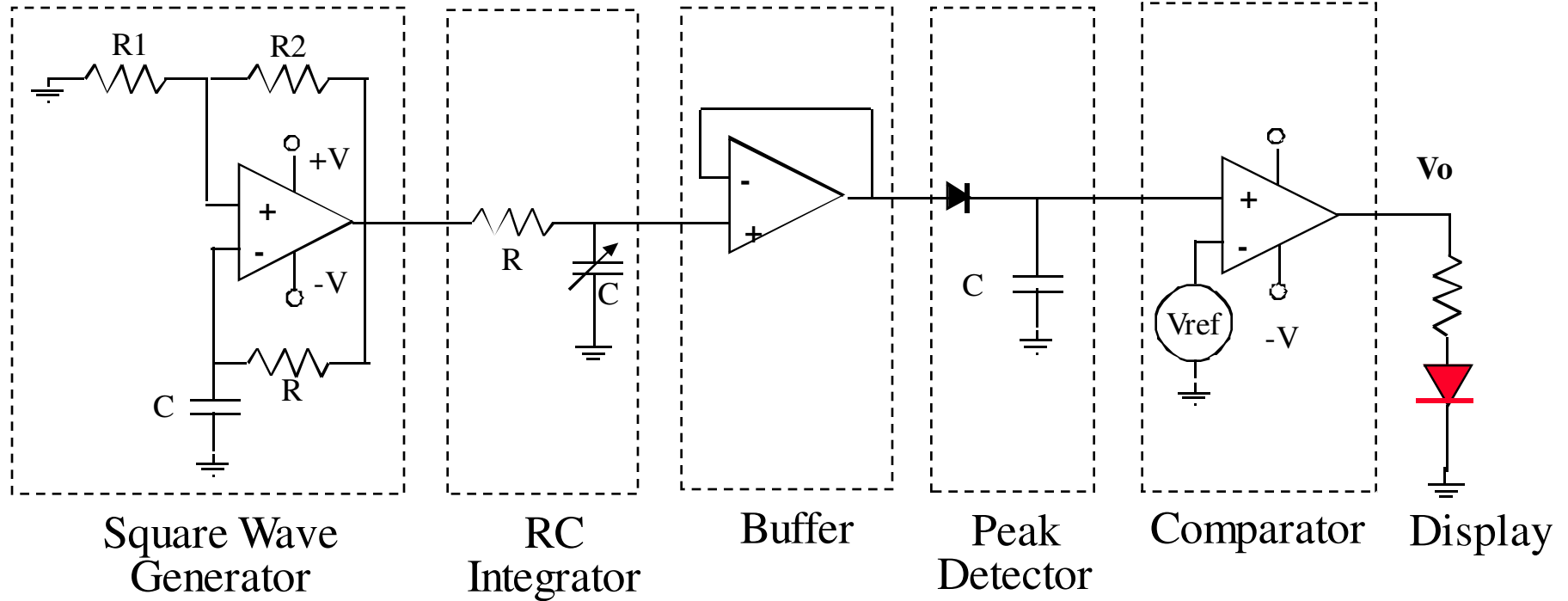


OSCILLATOR USING BISTABLE MULTIVIBRIATOR



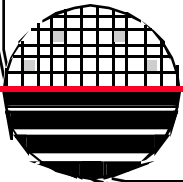
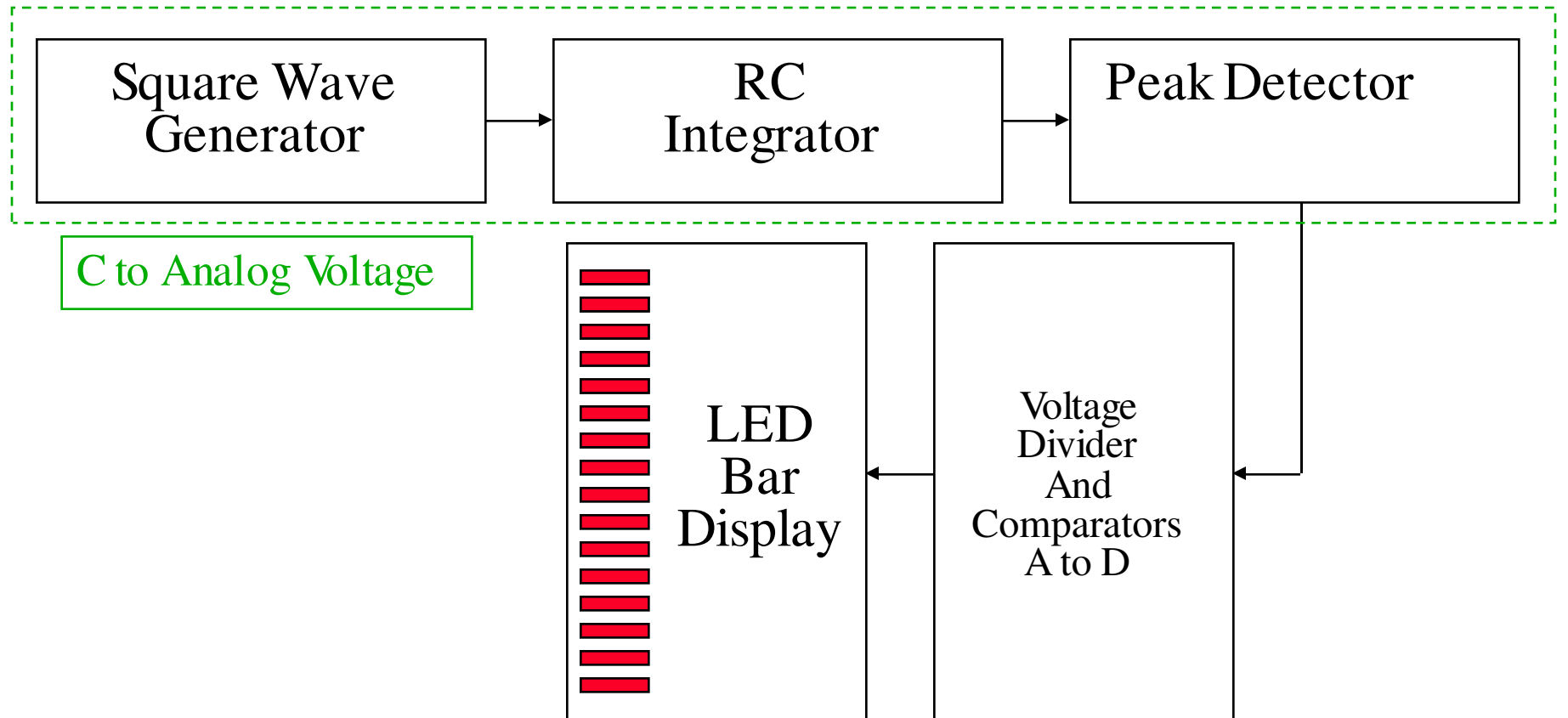
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LIQUID LEVEL DETECTOR



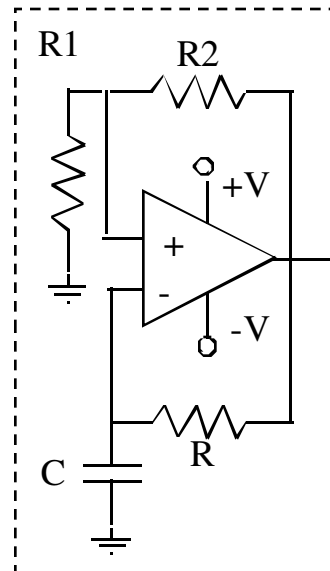
MEMS Capacitor Sensors

CAPACITANCE TO ANALOG VOLTAGE TO DIGITAL

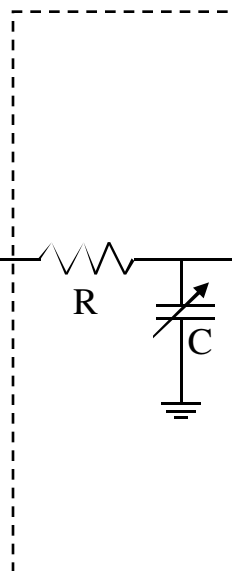


MEMS Capacitor Sensors

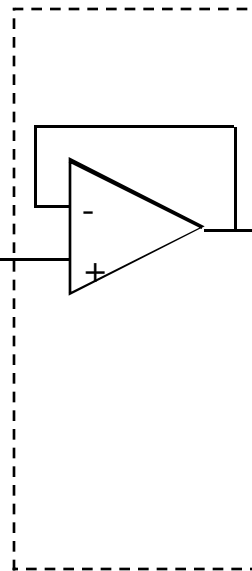
CAPACITOR SENSOR ELECTRONICS



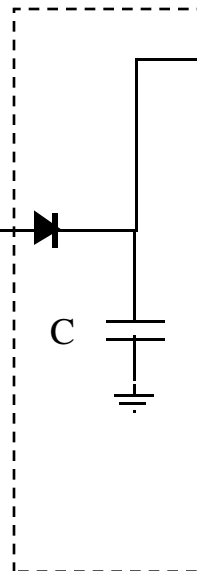
Square Wave Generator



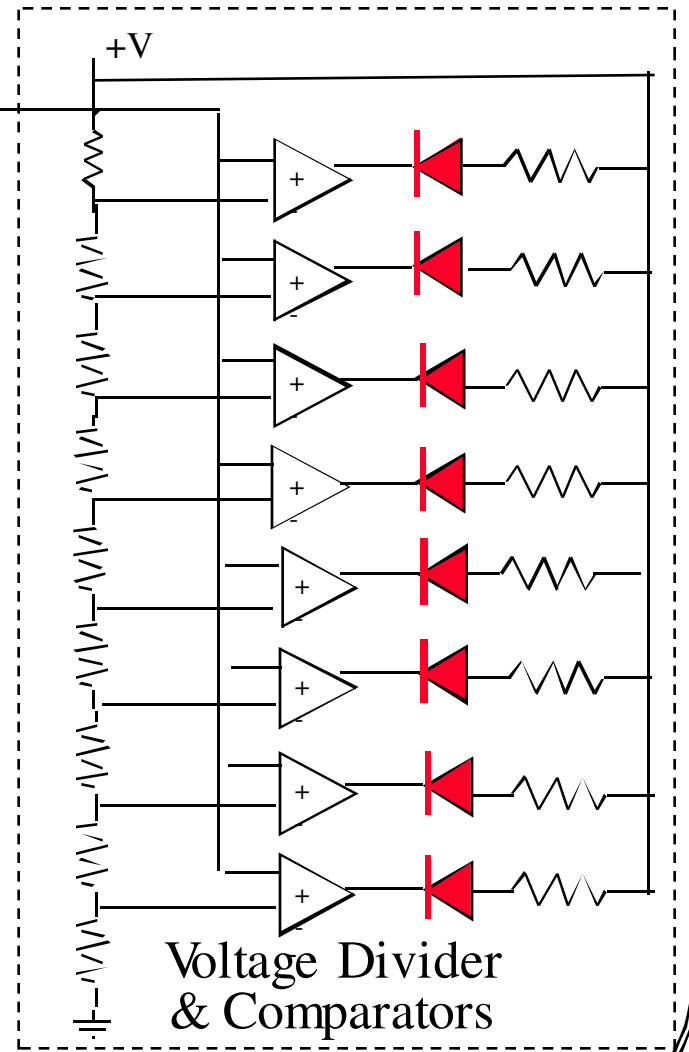
RC Integrator



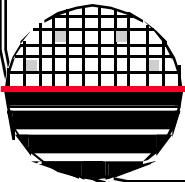
Buffer



Peak Detector

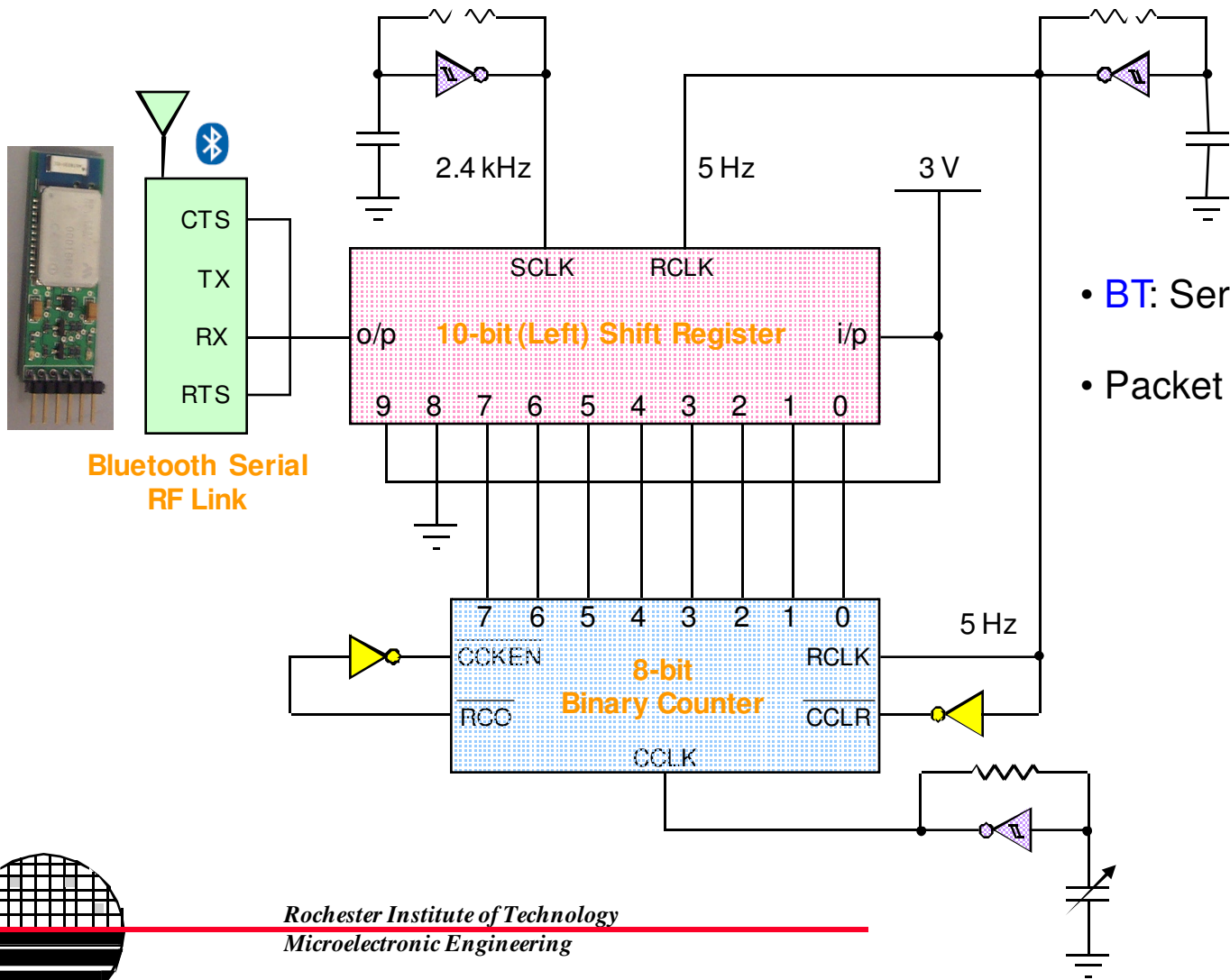


Voltage Divider & Comparators



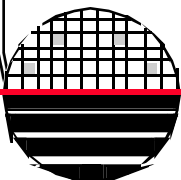
MEMS Capacitor Sensors

BLUETOOTH WIRELESS CAPACITOR SENSOR



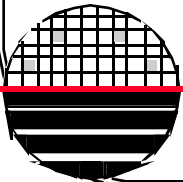
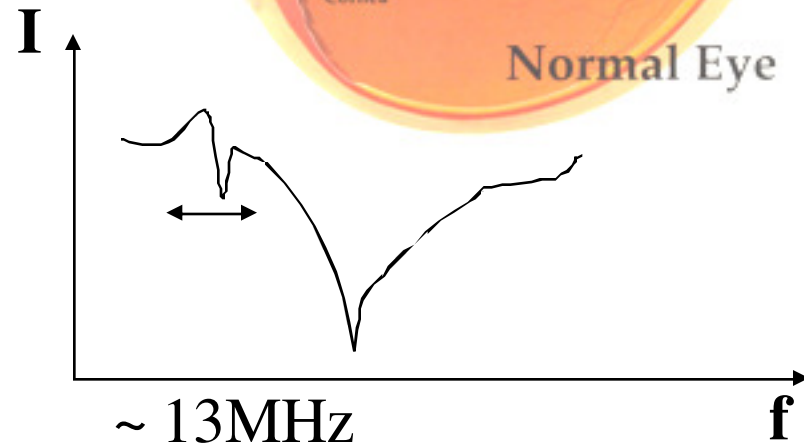
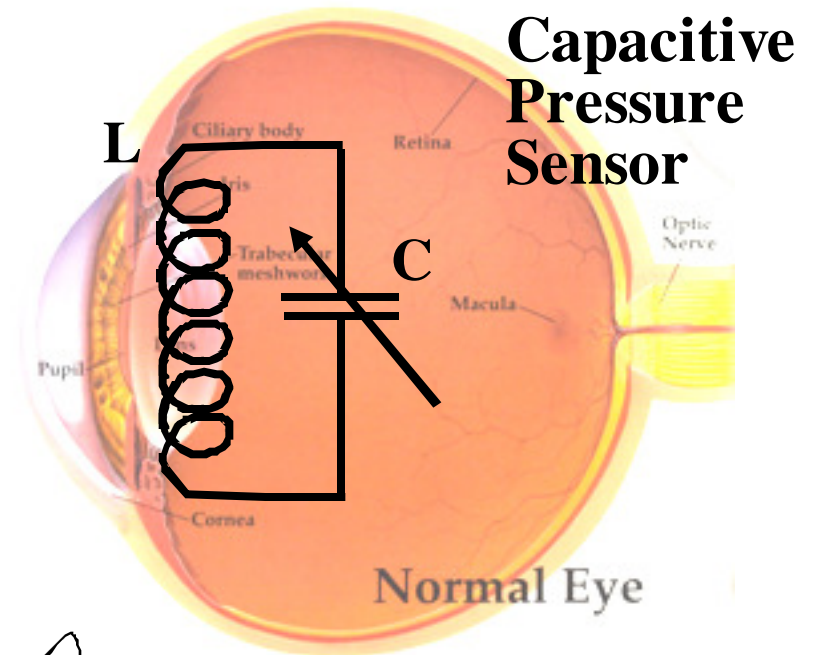
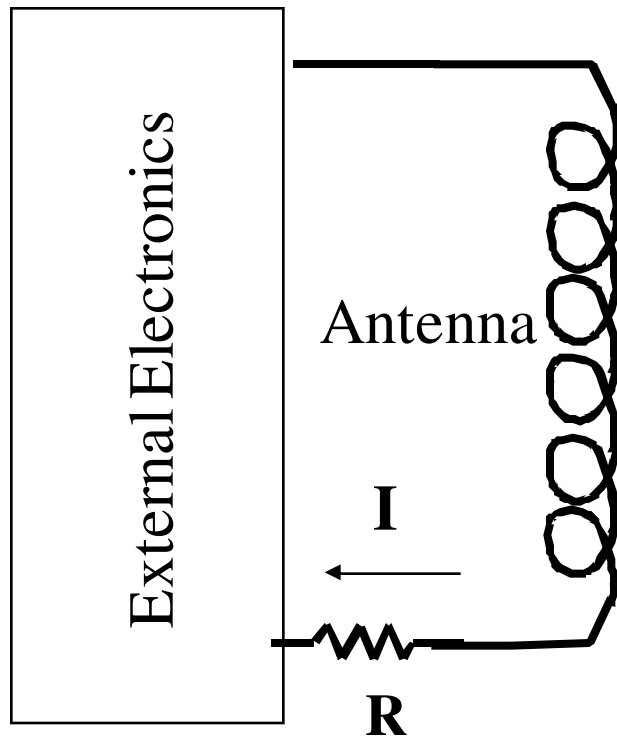
Bluetooth Serial RF Link

- BT: Serial Port Profile (RS232)
- Packet Specification :
 - Baud rate: 2400
 - Data bits: 8
 - Parity: None
 - Stop bits: 1



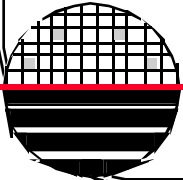
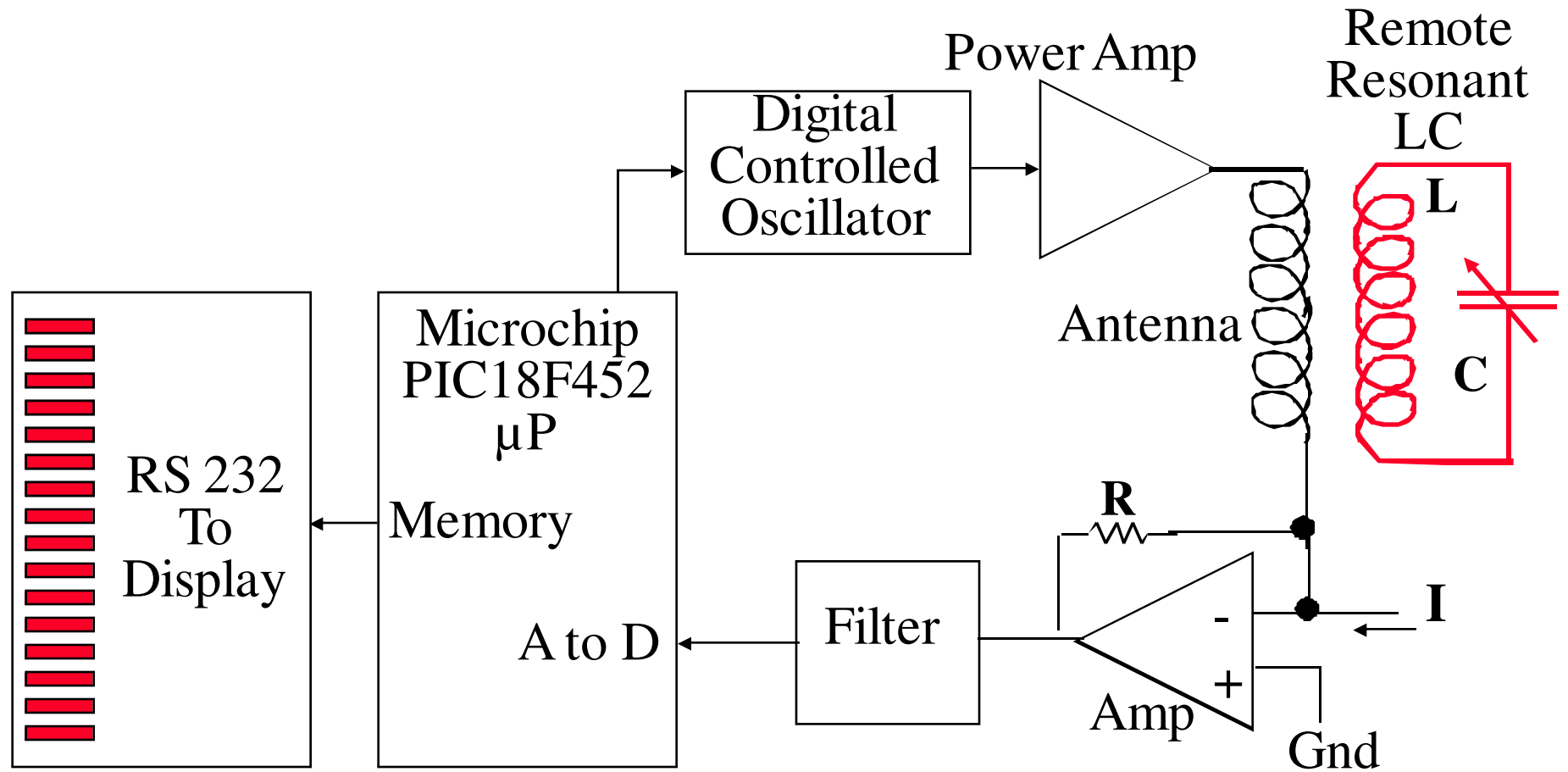
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WIRELESS REMOTE SENSING OF L OR C



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BLOCK DIAGRAM FOR REMOTE SENSING ELECTRONICS



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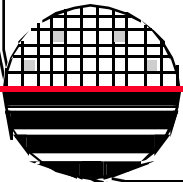
SIMILAR IDEA FOR WIRELESS TEMPERATURE



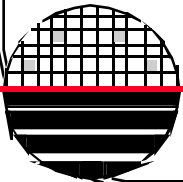
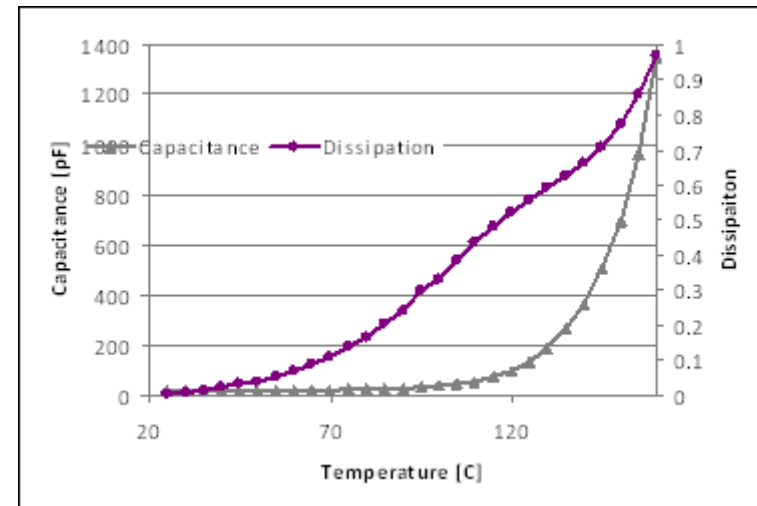
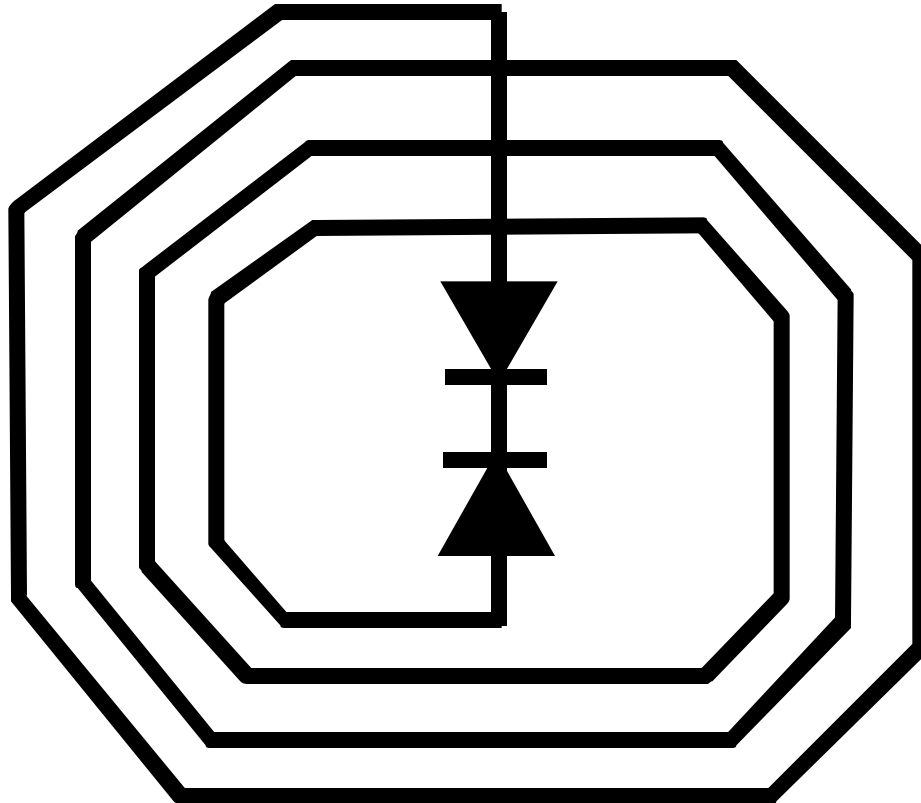
Network Analyzer



I vs. Frequency



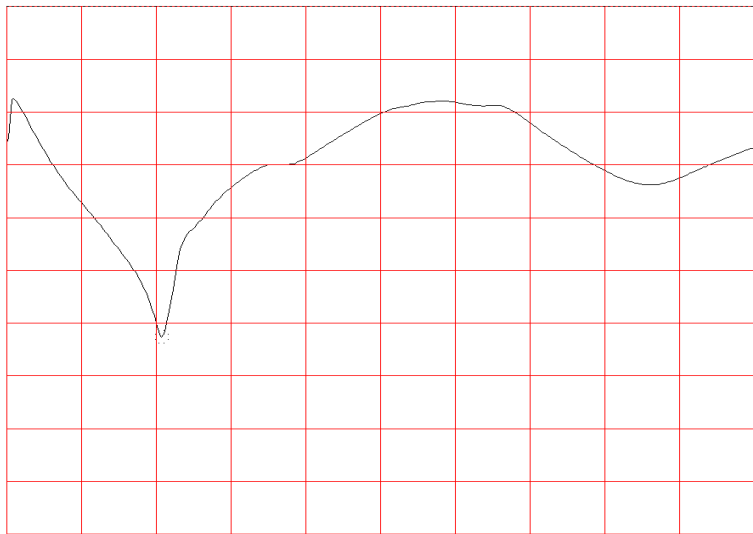
TEMPERATURE SENSING WITH COIL AND DIODES



MEMS Capacitor Sensors

PICKUP COIL CURRENT

REF LEVEL /DIV MARKER 41 500 000.000Hz
0.000dBm 10.000dB MAG(R) -62.626dBm

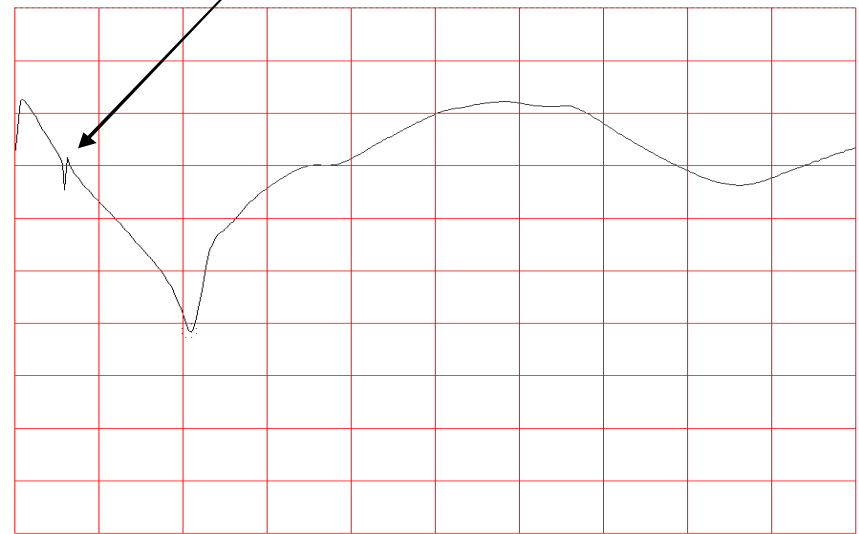


START 0.000Hz STOP 200 000 000.000Hz
AMPTD -10.0dBm

No Resonant Circuit Present

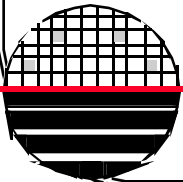
REF LEVEL /DIV MARKER 41 500 000.000Hz
0.000dBm 10.000dB MAG(R) -61.426dBm

Due to nearby LC



START 0.000Hz STOP 200 000 000.000Hz
AMPTD -10.0dBm

Resonant LC Circuit Present



MEMS Capacitor Sensors

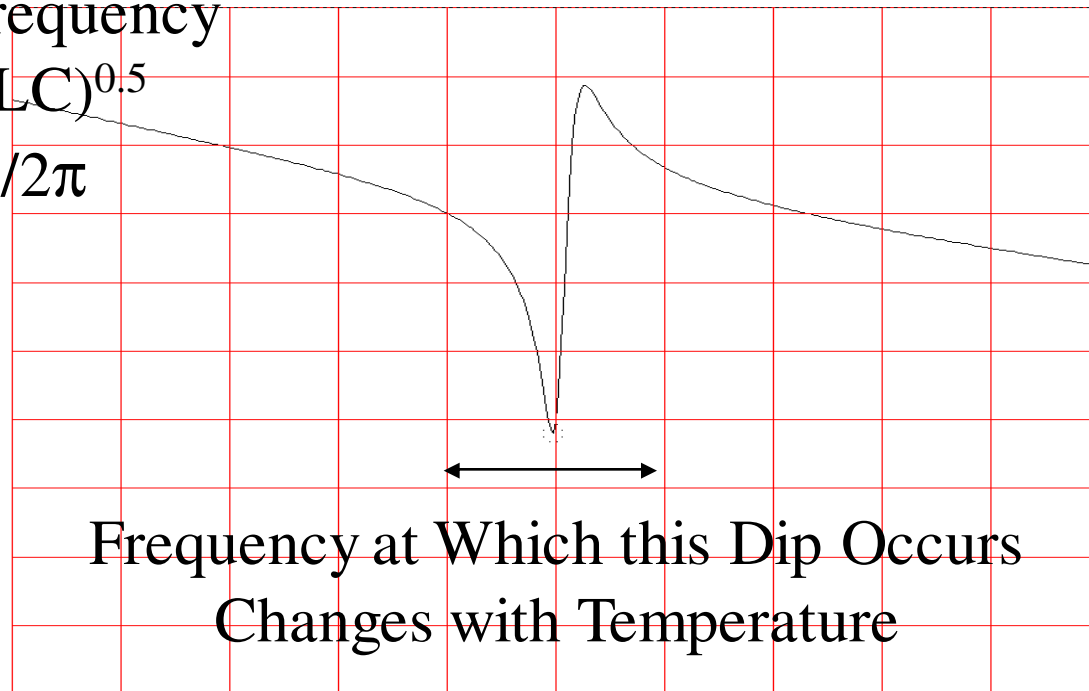
ZOOM IN ON RESONANCE DUE TO LC

REF LEVEL / DIV MARKER 11 837 500.000Hz
-22.000dBm 2.000dB MAG (R) -34.388dBm

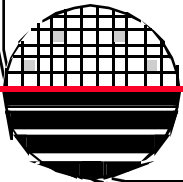
Resonant Frequency

$$\omega_0 = 1/(LC)^{0.5}$$

$$f_0 = \omega_0/2\pi$$



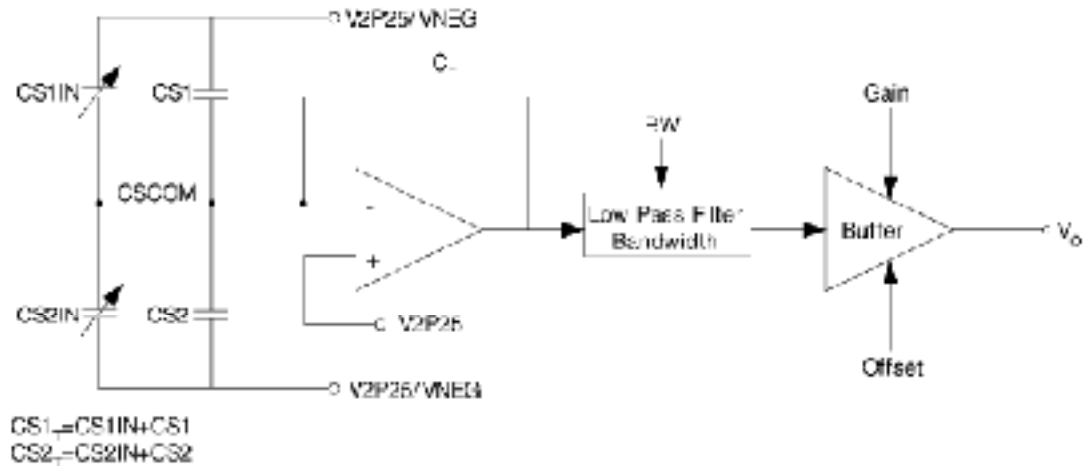
CENTER 11 850 000.000Hz SPAN 5 000 000.000Hz
AMP T D 0.2419 dBm



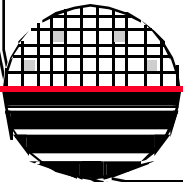
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COMMERCIAL CHIPS

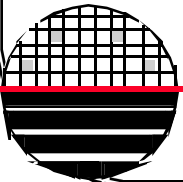


MS3110 Universal Capacitive Read-out IC (left) and its block diagram (right).

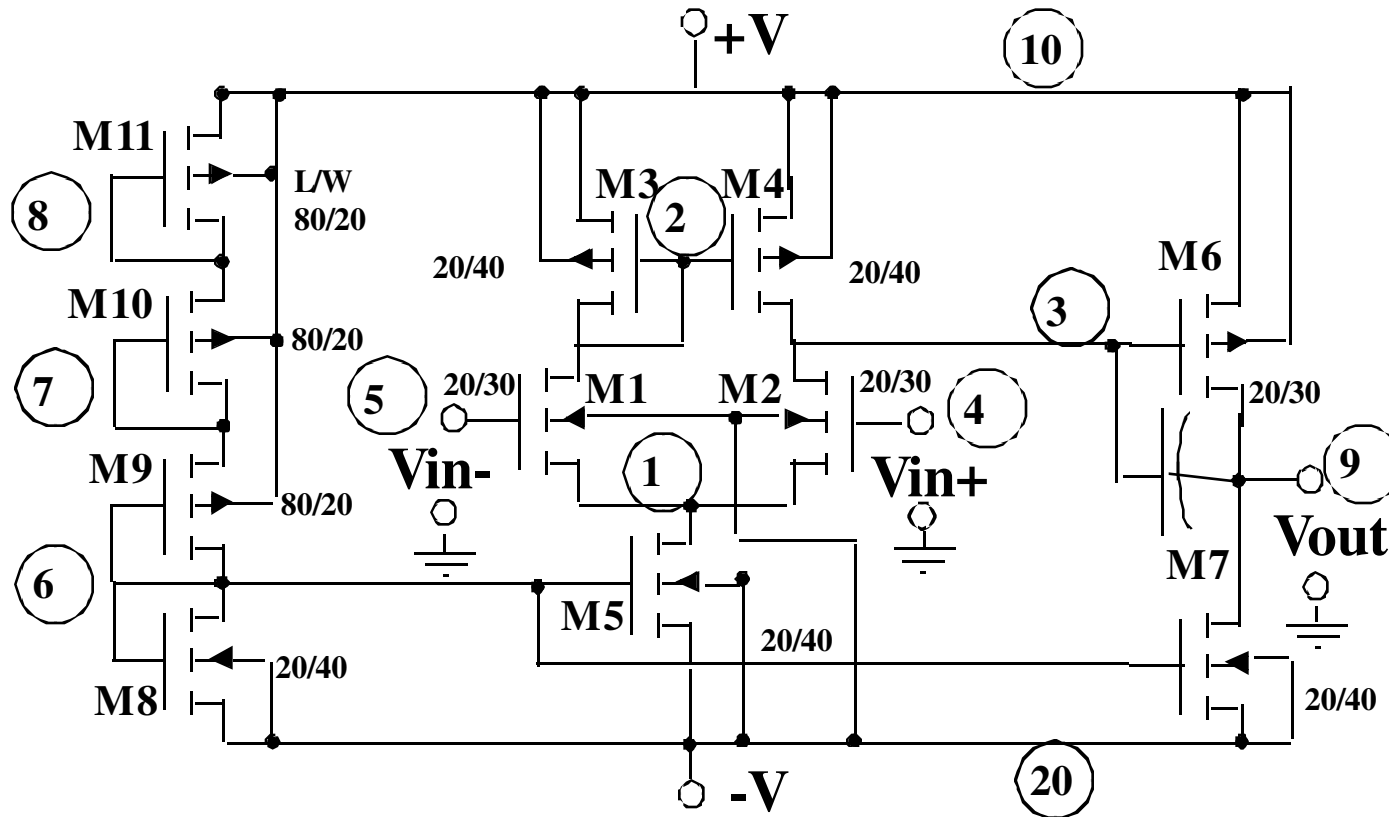


SIGNAL CONDITIONING BUILDING BLOCKS

Operational Amplifier
Analog Switches
Non-Overlapping Clock



CMOS OPERATIONAL AMPLIFIER

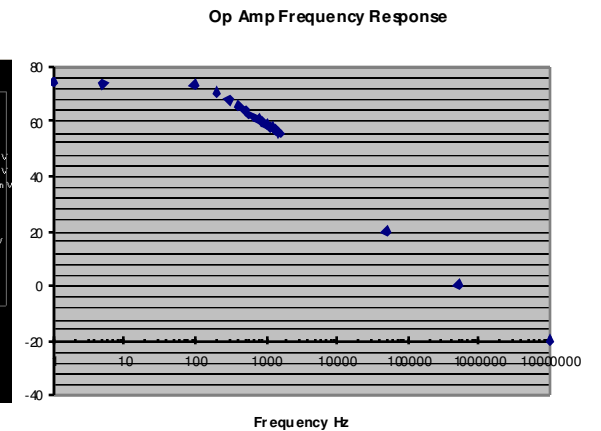
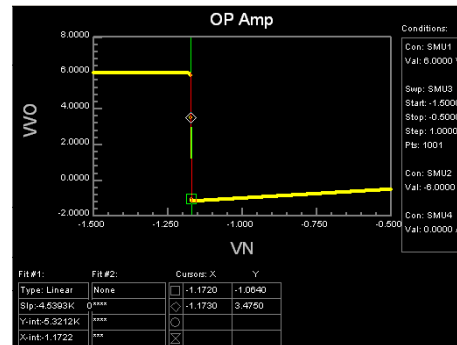
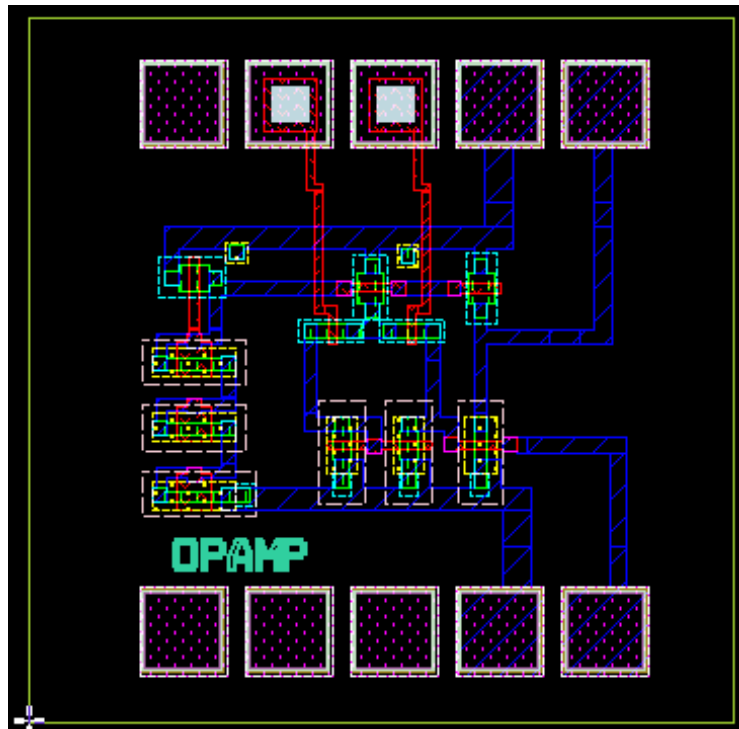


p-well CMOS

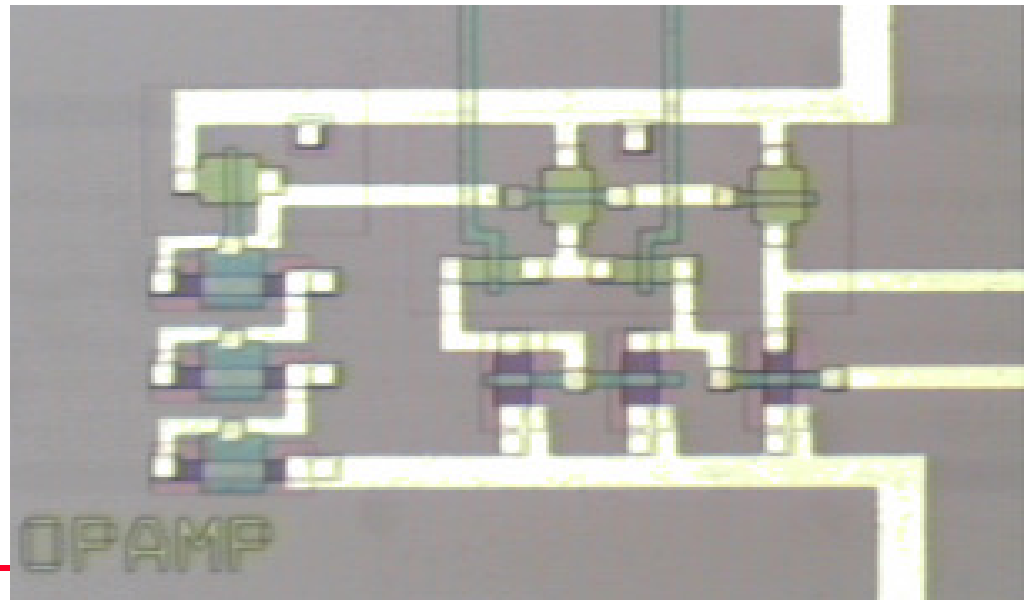
dimensions
L/W
($\mu\text{m}/\mu\text{m}$)

MEMS Capacitor Sensors

VERSION 1 OP AMP



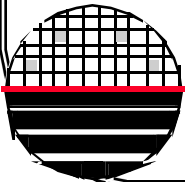
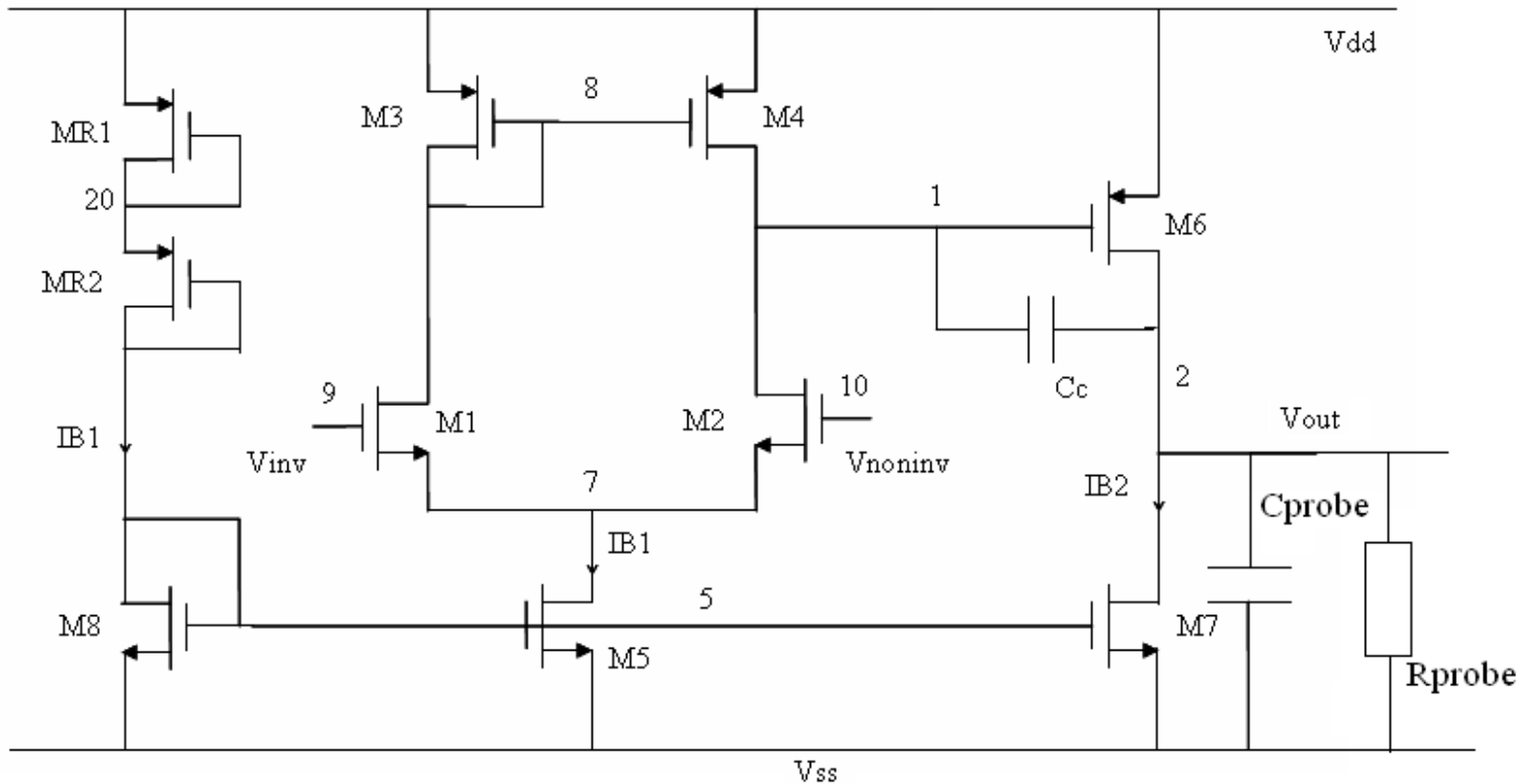
Gain ~5000
Offset 1.17 mV
GBW = 500KHz



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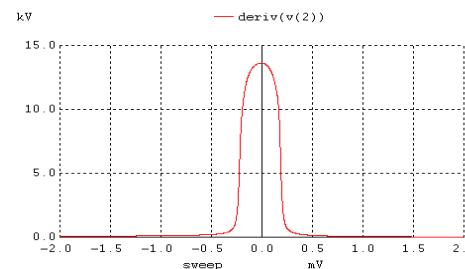
MEMS Capacitor Sensors

BASIC TWO STAGE OPERATIONAL AMPLIFIER



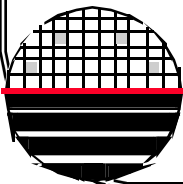
SPICE ANALYSIS OF OP AMP VERSION 2

```
.incl rit_sub_param.txt
m1 8 9 7 6 cmosn w=9u l=5u nrd=1 nrs=1 ad=45p pd=28u as=45p ps=28u
m2 1 10 7 6 cmosn w=9u l=5u nrd=1 nrs=1 ad=45p pd=28u as=45p ps=28u
m3 8 8 4 4 cmosp w=21u l=5u nrd=1 nrs=1 ad=102p pd=50u as=102p
ps=50u
m4 1 8 4 4 cmosp w=21u l=5u nrd=1 nrs=1 ad=102p pd=50u as=102p
ps=50u
m5 7 5 6 6 cmosn w=40u l=5u nrd=1 nrs=1 ad=205p pd=90u as=205p
ps=90u
m6 2 1 4 4 cmosp w=190u l=5u nrd=1 nrs=1 ad=950p pd=400u as=950p
ps=400u
m7 2 5 6 6 cmosn w=190u l=5u nrd=1 nrs=1 ad=950p pd=400u as=950p
ps=400u
m8 5 5 6 6 cmosn w=40u l=5u nrd=1 nrs=1 ad=205p pd=90u as=205p
ps=90u
vdd 4 0 3
vss 6 0 -3
cprobe 2 0 30p
Rprobe 2 0 1meg
cc 1 2 0.6p
mr1 20 20 4 4 cmosp w=6u l=10u nrd=1 nrs=1 ad=200p pd=60u as=200p
ps=60u
mr2 5 5 20 4 cmosp w=6u l=10u nrd=1 nrs=1 ad=200p pd=60u as=200p
ps=60u
*****
*****
```



13.5kV/V gain

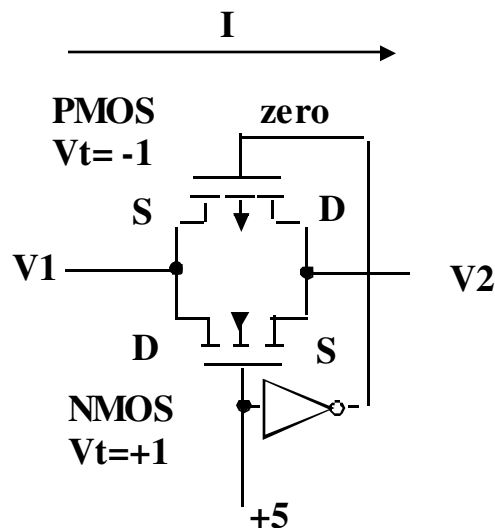
```
***dc open loop gain*****
vi1 9 0 0
vi2 10 0 0
*.dc vi2 -0.002 0.002 1u
.dc vi2 -1 1 0.1m
*****open loop frequency
characteristics*****
*vi1 9 0 0
*vi2 10 0 dc 0 ac 1u
*.ac dec 100 10 1g
.end
```



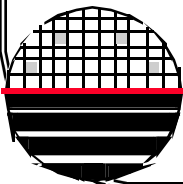
OPERATIONAL AMPLIFIER



ANALOG SWITCHES

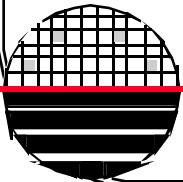
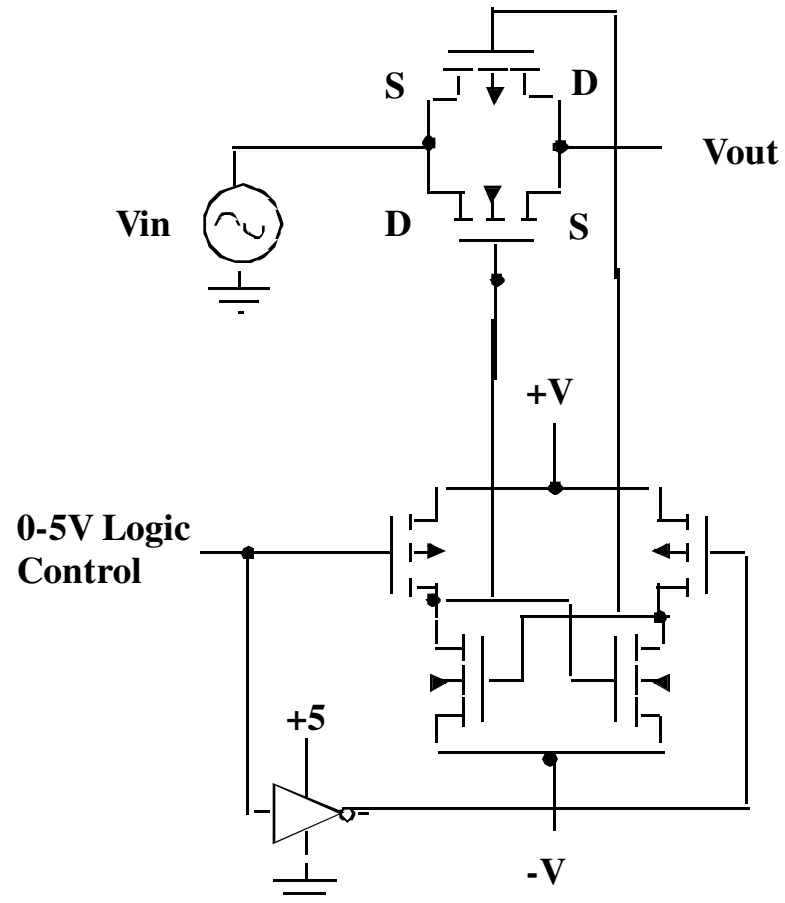


For current flowing to the right (ie $V1 > V2$) the PMOS transistor will be on if $V1$ is greater than the threshold voltage, the NMOS transistor will be on if $V2$ is < 4 volts. If we are charging up a capacitor load at node 2 to 5 volts, initially current will flow through NMOS and PMOS but once $V2$ gets above 4 volts the NMOS will be off. If we are trying to charge up $V2$ to $V1 = +1$ volt the PMOS will never be on. A complementary situation occurs for current flow to the left. Single transistor switches can be used if we are sure the V_{gs} will be more than the threshold voltage for the specific circuit application. (or use larger voltages on the gates)



MEMS Capacitor Sensors

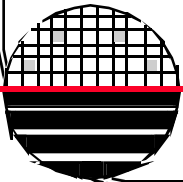
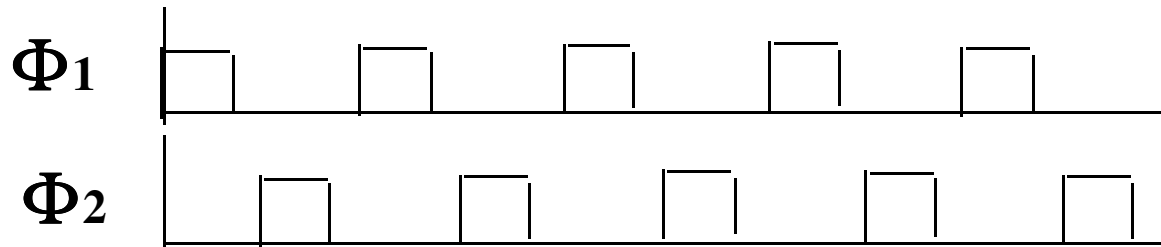
(+V to -V) ANALOG SWITCH WITH (0 to 5 V) CONTROL



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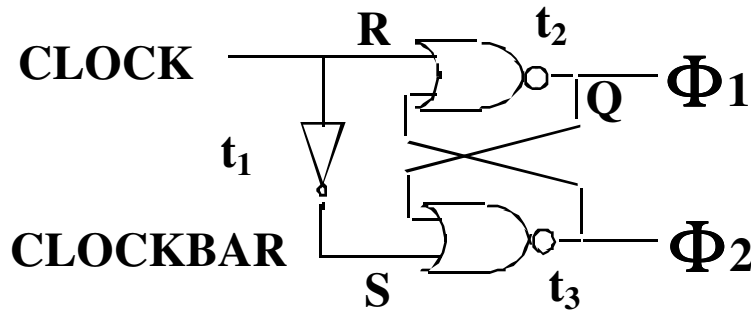
TWO PHASE NON OVERLAPPING CLOCK

Synchronous circuits that use the two phase non overlapping clock can separate input quantities from output quantities used to calculate the results in feedback systems such as the finite state machine.

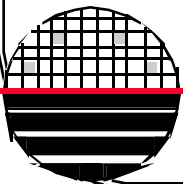
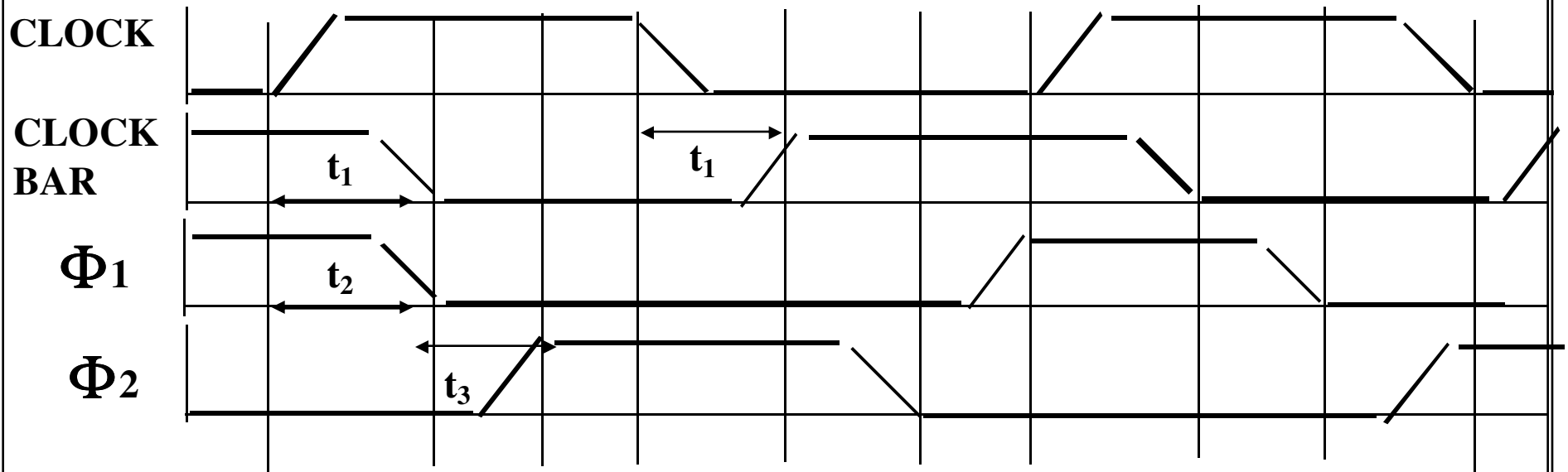


TWO-PHASE CLOCK GENERATORS

A	B	C
0	0	1
0	1	0
1	0	0
1	1	0

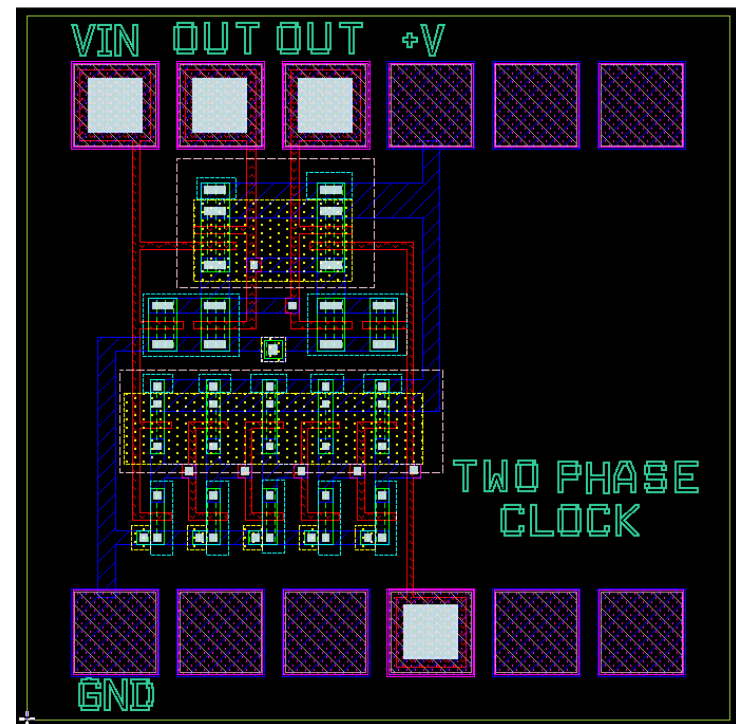
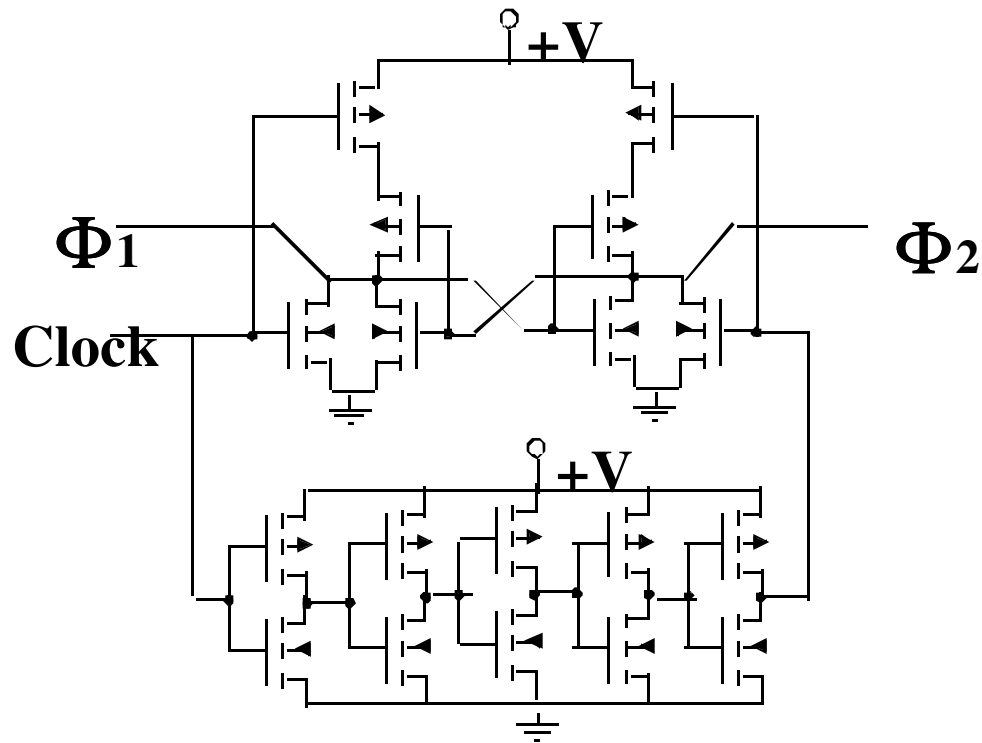


R	S	Q
0	0	Q_{n-1}
0	1	1
1	0	0
1	1	INDETERMINATE

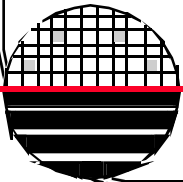


MEMS Capacitor Sensors

TRANSISTOR LEVEL SCHEMATIC OF 2 PHASE CLOCK

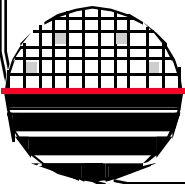
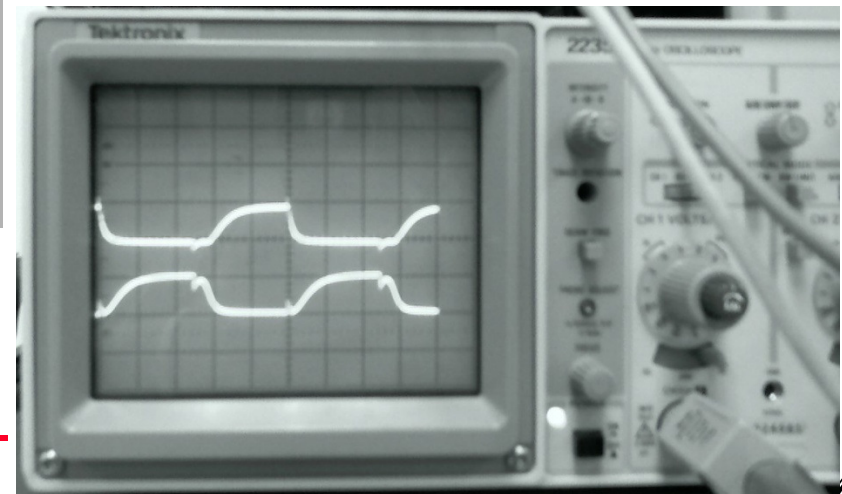
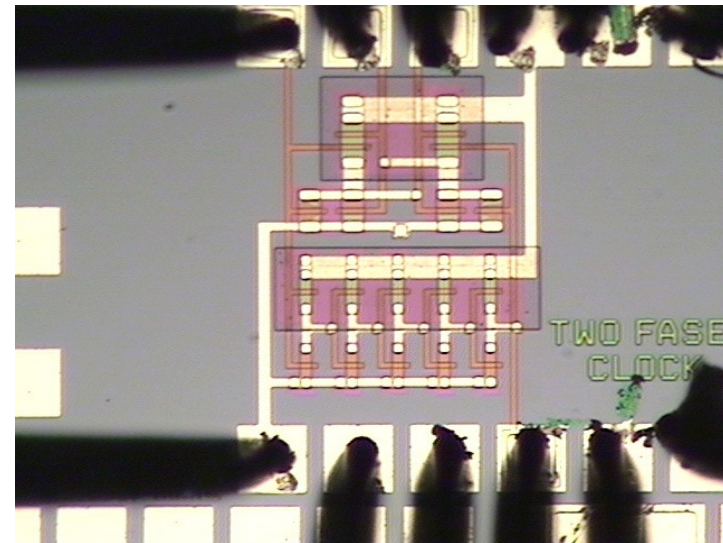
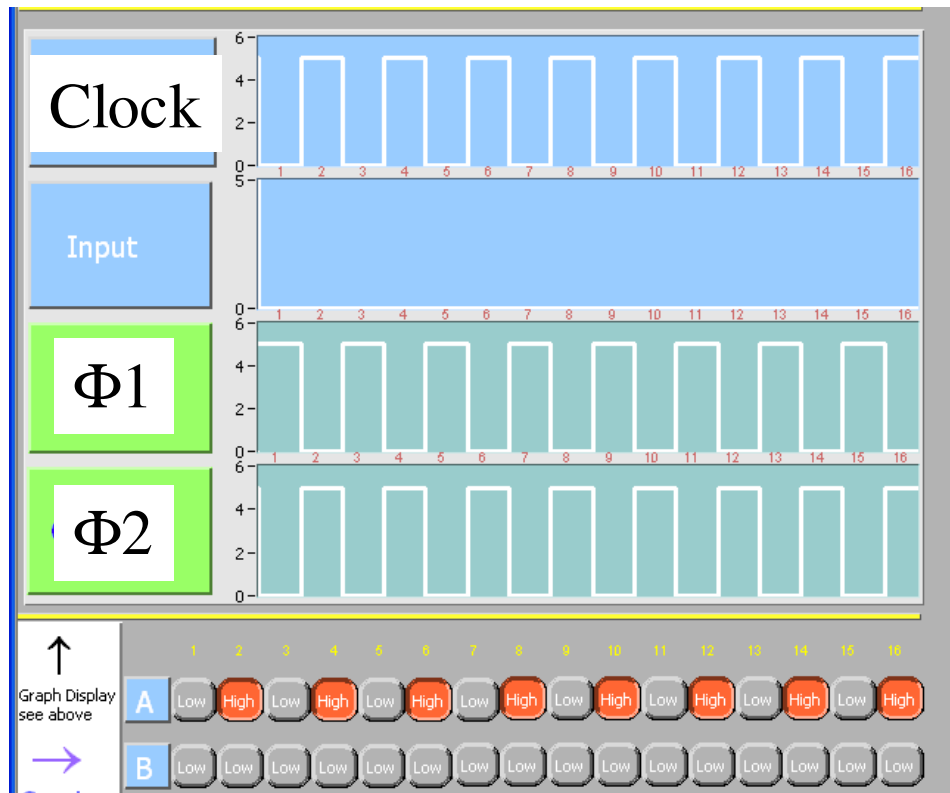


Layout



MEMS Capacitor Sensors

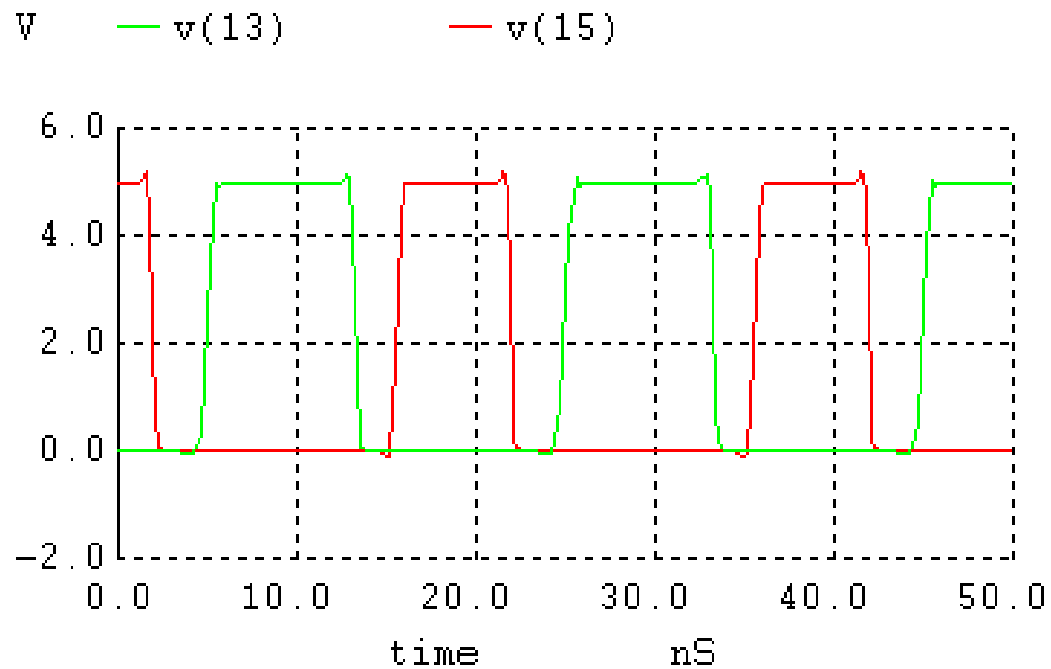
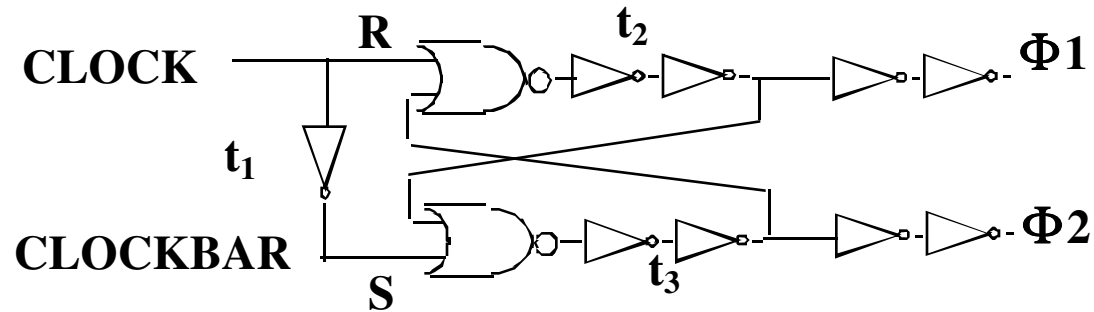
TWO PHASE NON OVERLAPPING CLOCK



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Microelectronic Engineering

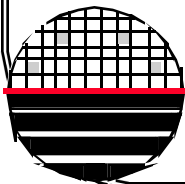
MEMS Capacitor Sensors

WINSPICE SIMULATION FOR VERSION TWO + BUFFERS



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HOMEWORK – MEMS CAPACITOR SENSORS

1. Calculate the capacitance for a round plate of $100\mu\text{m}$ diameter with an air gap space of $2.0\mu\text{m}$.
2. If the capacitor in 1 above has the air gap replaced by water what will the capacitance be?
3. Design an apparatus that can be used to illustrate the attractive force between two parallel plates when a voltage is applied.
4. Design an electronic circuit that can measure the capacitance of two metal plates (the size of a quarter) separated by a thin foam insulator for various applied forces.

